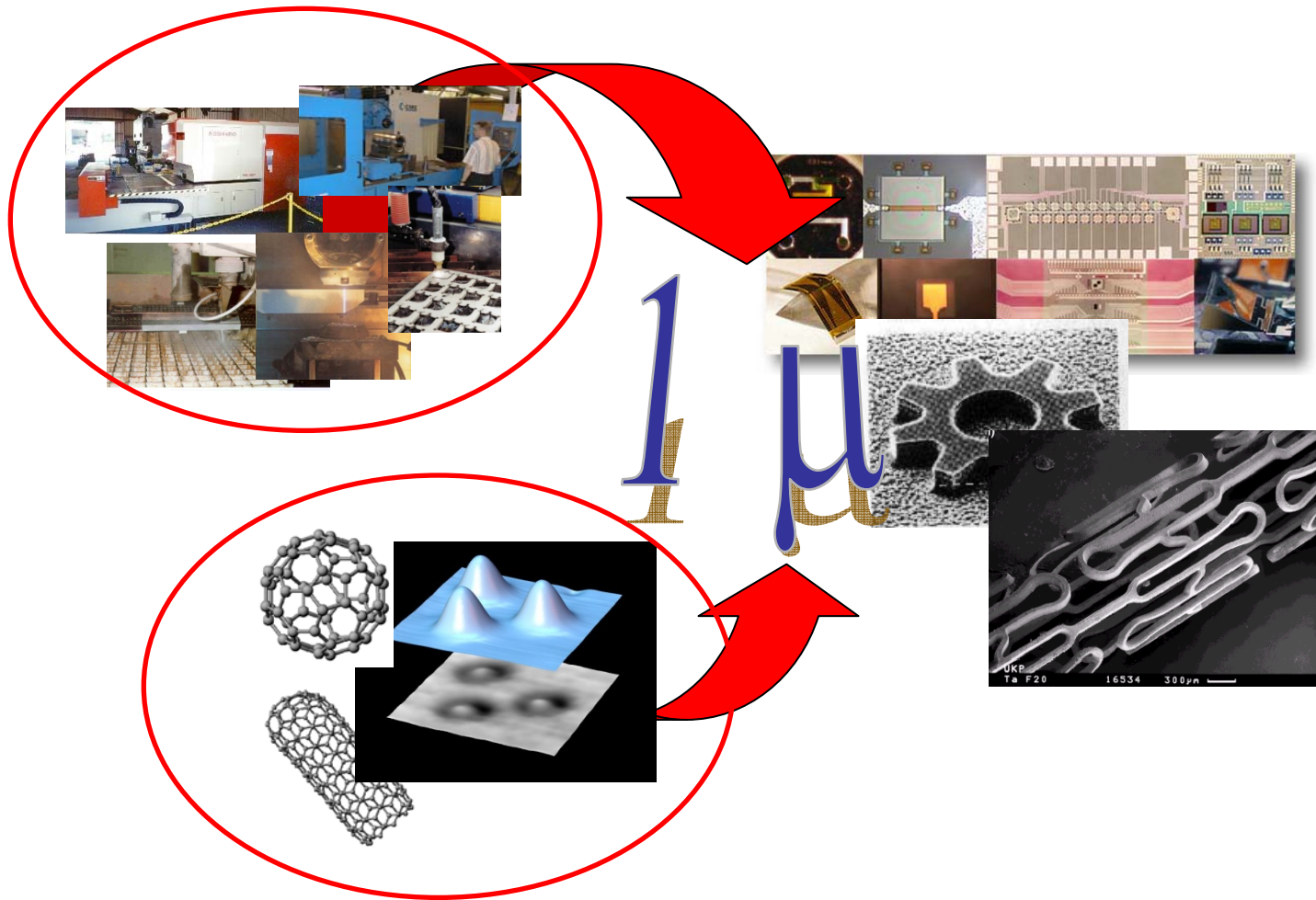


Application of high intensity short pulse lasers to precision micromanufacturing

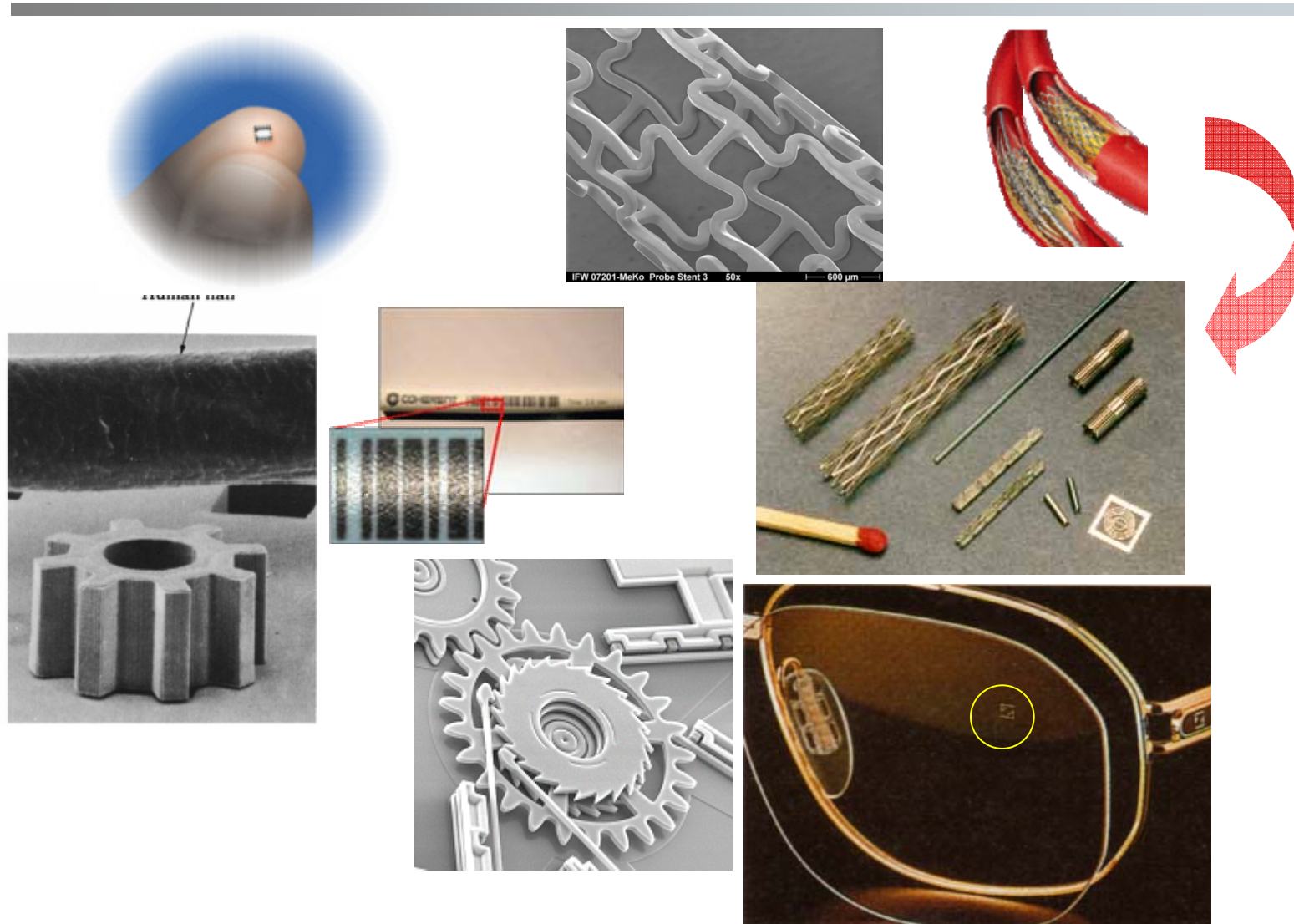
J.L. Ocaña, C. Molpeceres, M. Morales, M. Holgado, J.J. García-Ballesteros, S. Lauzurica, J.A. Porro, O. García, D. Iordachescu

*ETSII-Dept. of Applied Physics and UPM Laser Centre
Universidad Politécnica de Madrid
ETSII-UPM, C/ José Gutiérrez Abascal, 2. E-28006 Madrid. SPAIN
Tel.: (+34) 913363099. Fax: (+34) 913363000. email: jlocana@etsii.upm.es*

1 μm : LOOKING FOR SUITABLE FABRICATION TOOLS



1 μm : LOOKING FOR SUITABLE FABRICATION TOOLS



1 μm : MICRO-PROCESSING ADVANTAGES

1. High density of energy – required by very hard materials
2. Precision & repeatability
3. Enabled for high-selective ablation
4. Not intrusive – high flexibility noncontact machining
5. Very reduced HAZ

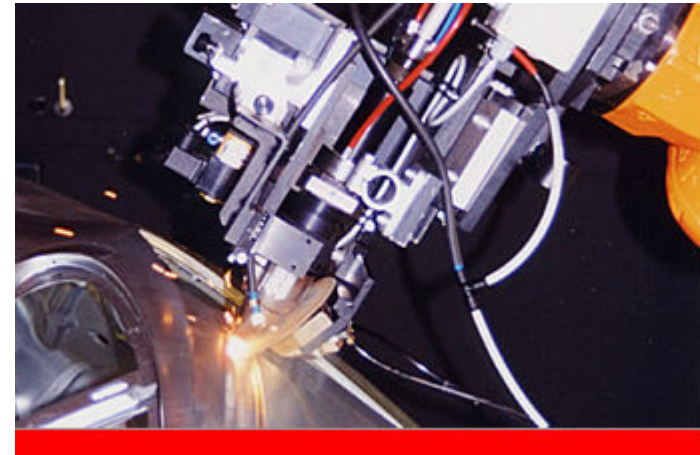
LASER MICRO vs MACROMACHINING

Are laser systems going to play the same role in micro applications that they played in macro-processing?



- Close tolerance
- Excellent repeatability
- Unit cost reductions
- Material versatility

- Clean processing to eliminate debris
- Flexibility - fast setups achievement
- Little or no burring or affected zones
- Fully 3D processing



LASER MICROMACHINING: A TECHNOLOGICAL INNOVATION?

Micromachining means cutting, welding, soldering, selective ablation, forming, patterning, etc, with dimensional details in the order of 1 μm .

- Excimer photolithography and selective ablation ~ 20 years
- Semiconductor applications *dicing, drilling, engraving, cutting, etc.* in Si, TCOs, etc. ~ 20 years
- *ps* and *fs* lasers applications ~ 15 years
- DPSS Q-switch multi kHz sources ~ 10 years

LASER MICROMACHINING FACTS

- Laser micromachining is intended mainly for material modification near the surface or for processing with high aspect ratios.
- Most present applications are **strictly 2D (planar or cylindrical) or are intended to process planar areas of 3D objects**. Presently an **increasing interest in fully 3D applications is developing, and in general, implying some serious mechanical problems**. These facts imply non trivial questions at the time of systems definition and design and, in particular, positioning systems characteristics and figures are of great transcendence, and not admitting simple scaled solutions from macroprocessing systems.

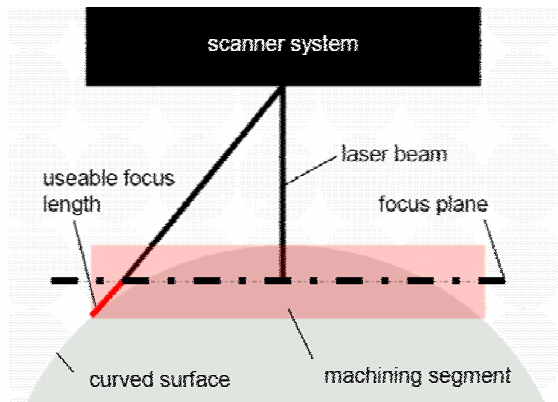
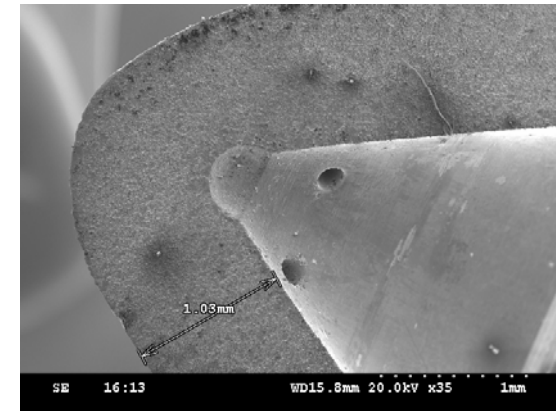


Fig. 4: Machining of a curved surface

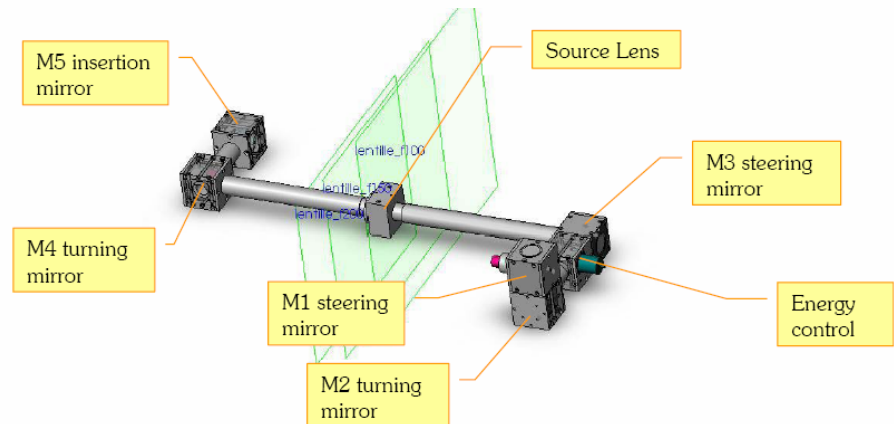
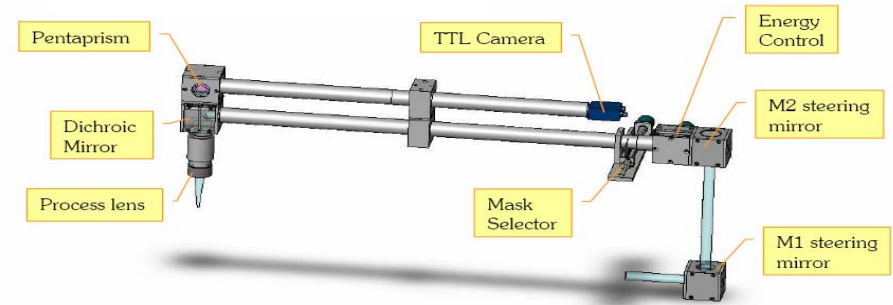


Thin Film and
Surface Engineering



Fuel injector section

CML-100



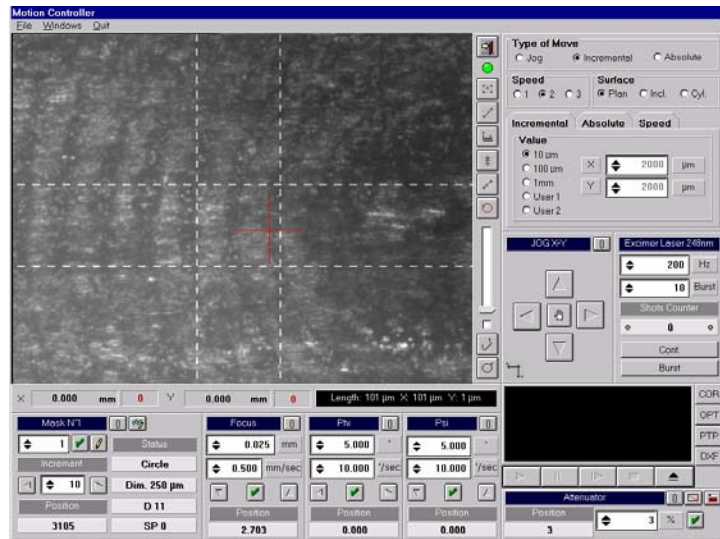
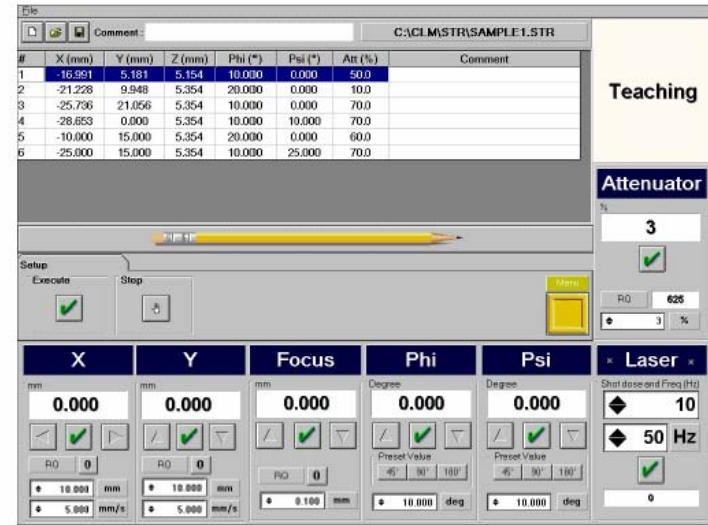
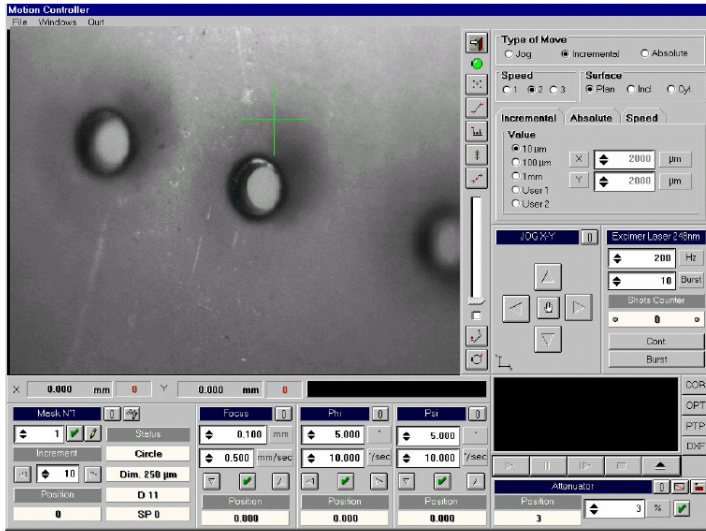
Multi-axis (6) system
with *ns* laser sources for focal point applications,
mask projection and hybrid techniques.

LASER PARAMETERS

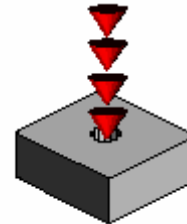
<i>Laser Media</i>	<i>Excimer (KrF)</i>	<i>DPSS 3ω (Nd: YVO₄)</i>	<i>DPSS 1ω (Nd: YAG)</i>
Wavelength (nm)	248	355	1064
Pulse Duration (ns)	3-7 ns	< 12 ns (@ 50 kHz)	< 70 ns (@ 7.5 kHz)
Beam shape/mode	Rectangular (3.5 x 6 mm)	TEM₀₀ (M² < 1.3)	TEM₀₀ (M² < 1.15)
Operating frequency	0-300 Hz	15 – 300 kHz	1-100 kHz
Average power (W)	0.3-5 (@ 300 Hz)	5 W (@ 50 kHz)	6.5 W (@ 50 kHz)

- DPSS (355 & 1064 nm): Focal point processing
- EXCIMER Irradiation (248 nm): Mask projection and hybrid techniques

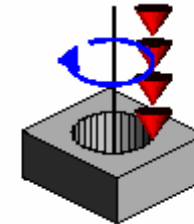
SOFTWARE FEATURES



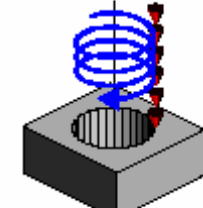
percussion



trepanning



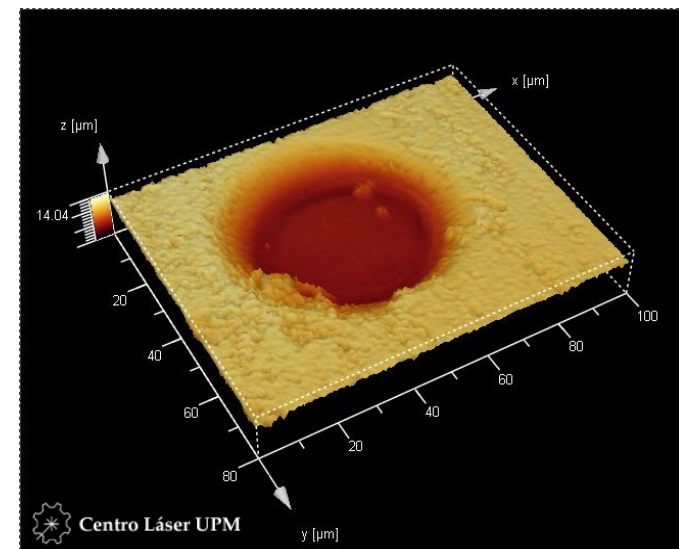
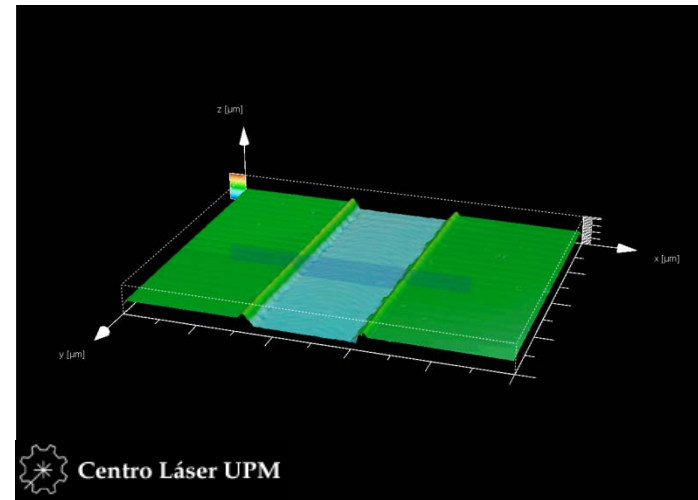
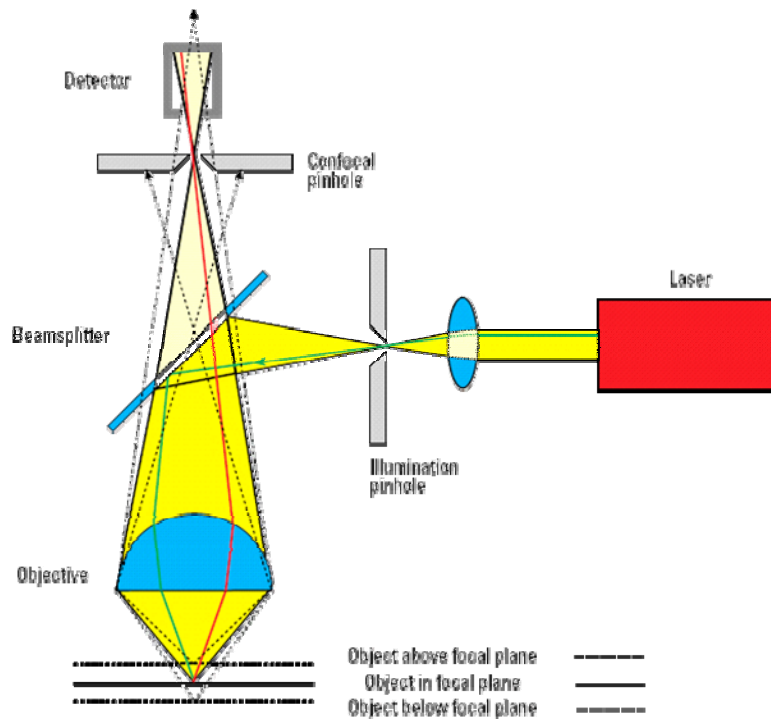
helical drilling



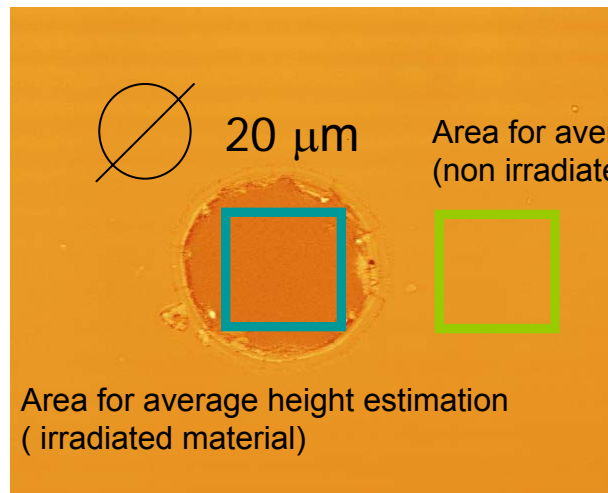
laser-erosion

WORKPIECE ANALYSIS AND MEASUREMENT

Confocal Laser Scanning Microscopy (Leica ICM 1000, $\lambda=635\text{ nm}$) and SEM imaging

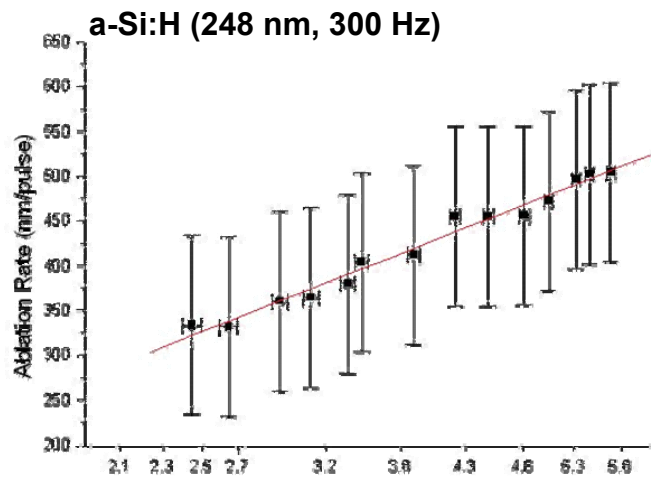


ABLATION CURVES MEASUREMENT

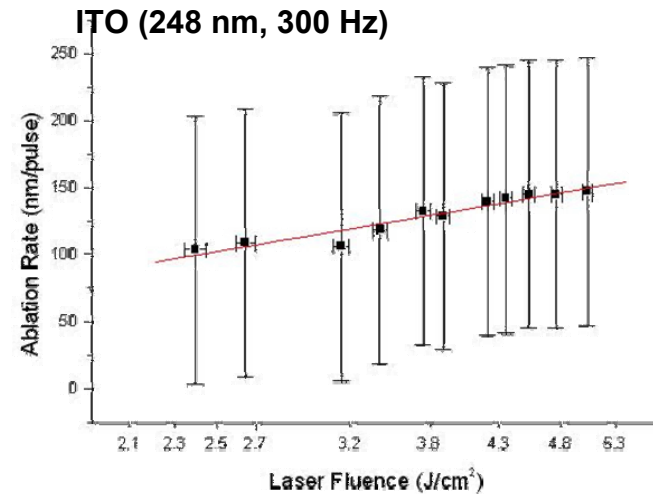


a.h. - a.h. = D (ABLATION DEPTH P.P.)

Expected accuracy:
> 20 nm in step measurements

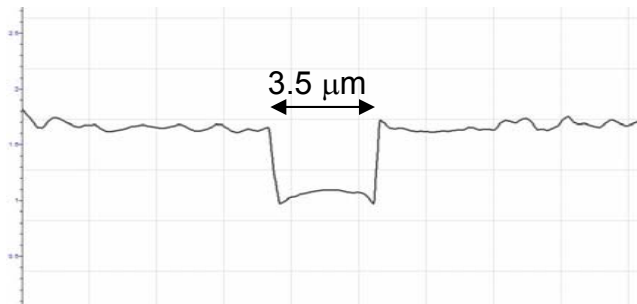
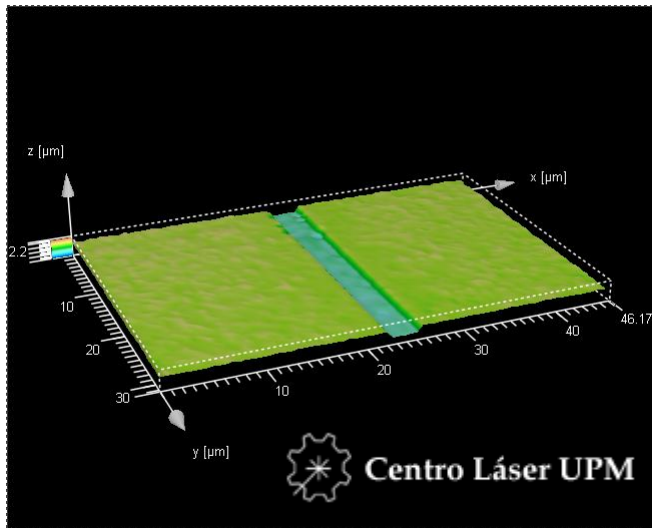


$\Phi_{Th} = 0.58 \pm 0.02 \text{ J/cm}^2$



$\Phi_{Th} = 0.47 \pm 0.02 \text{ J/cm}^2$

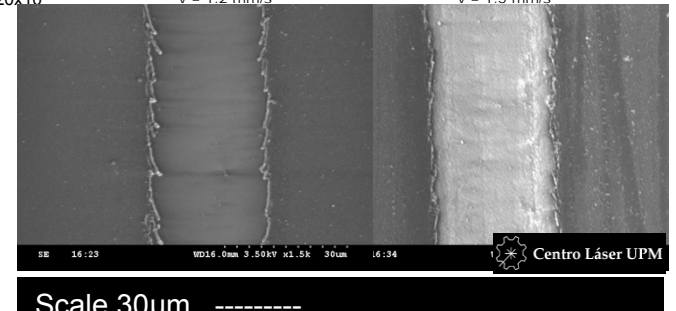
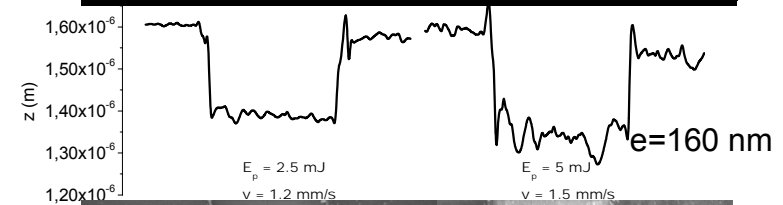
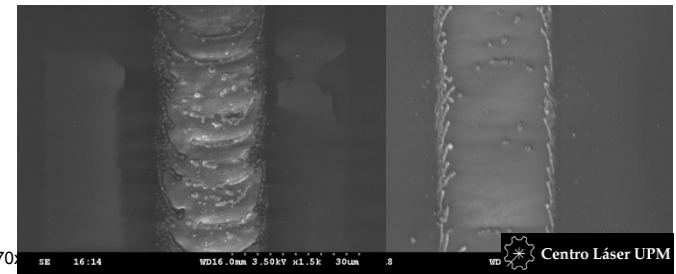
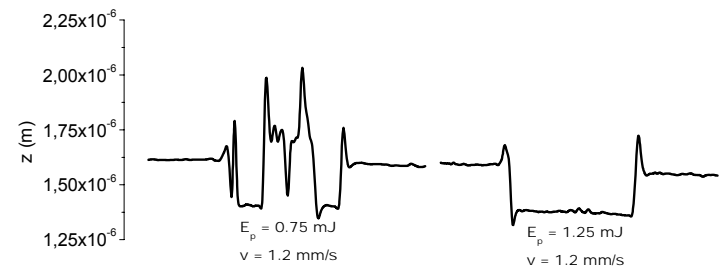
THIN FILM SELECTIVE ABLATION



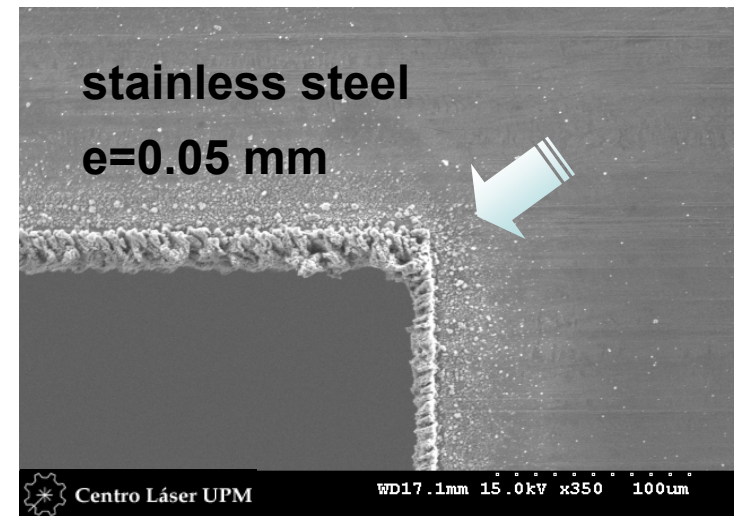
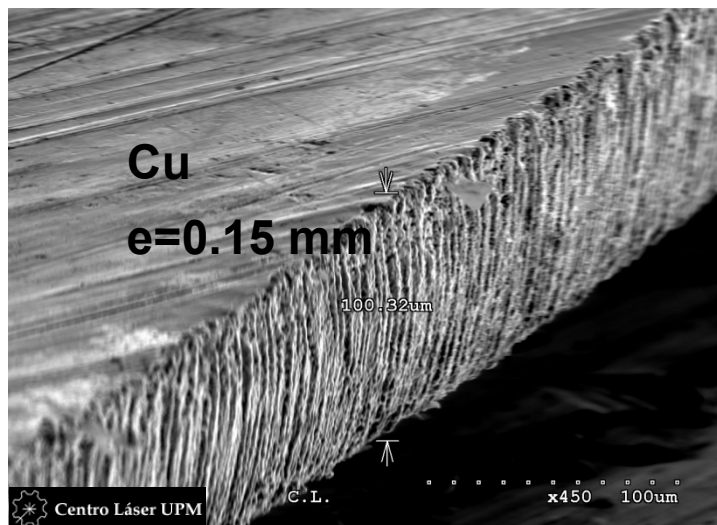
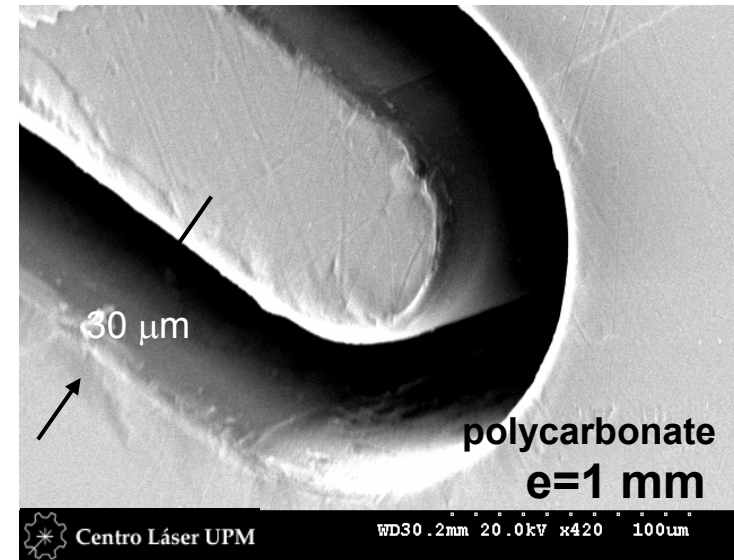
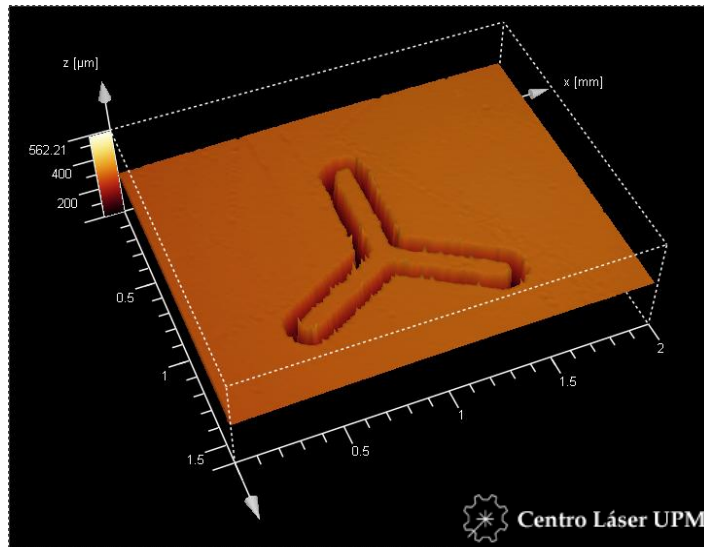
TCO SELECTIVE ABLATION

$e=500\text{ nm}$

a-Si SELECTIVE ABLATION



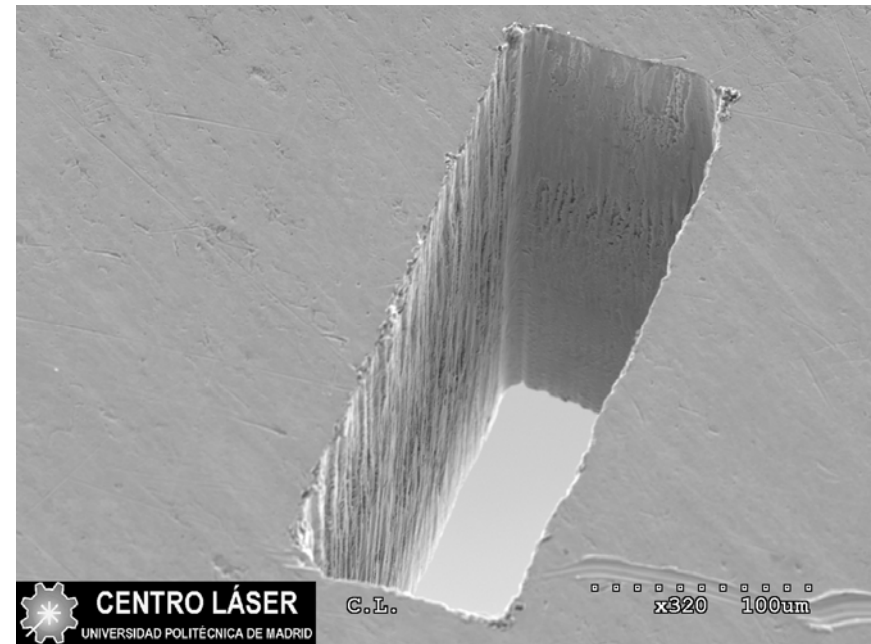
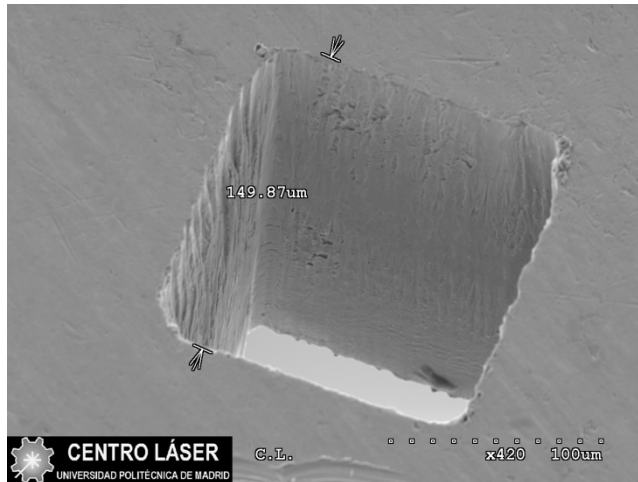
PLANAR CUTTING APPLICATIONS



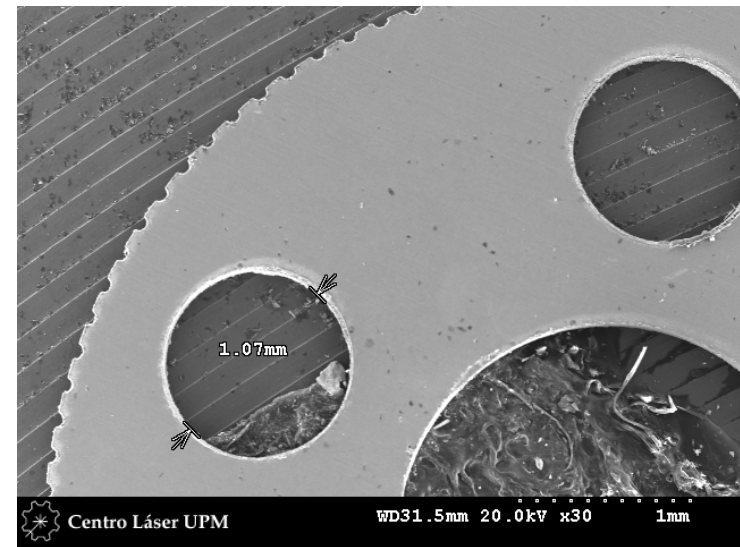
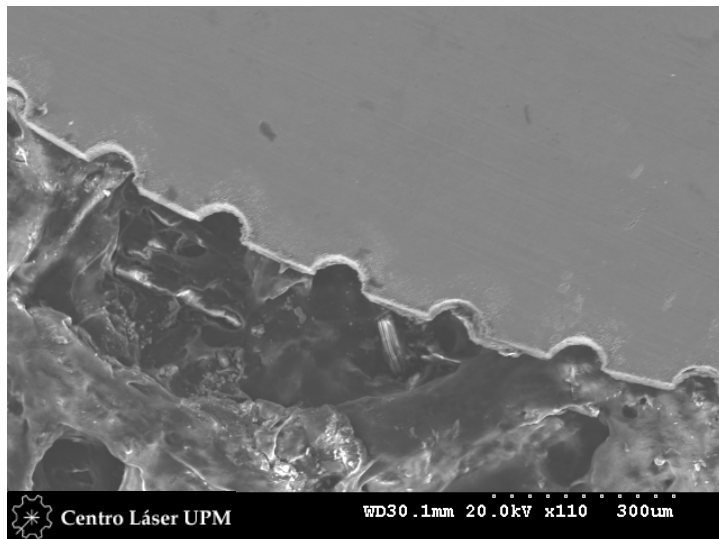
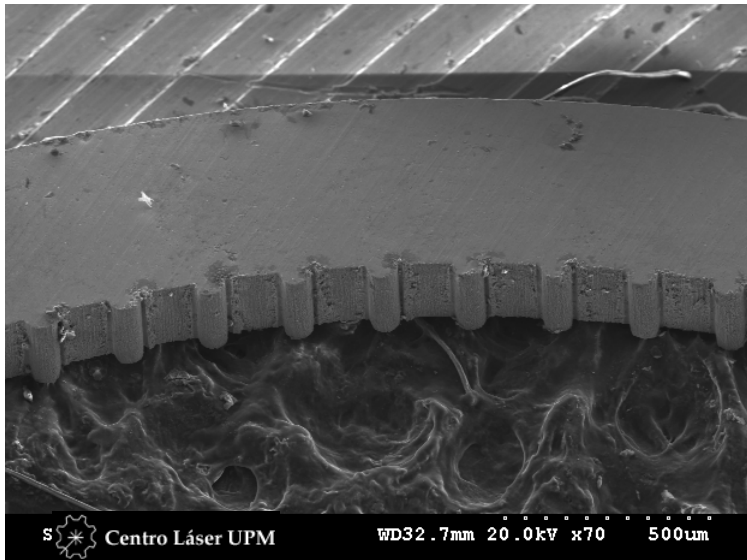
PLANAR CUTTING APPLICATIONS



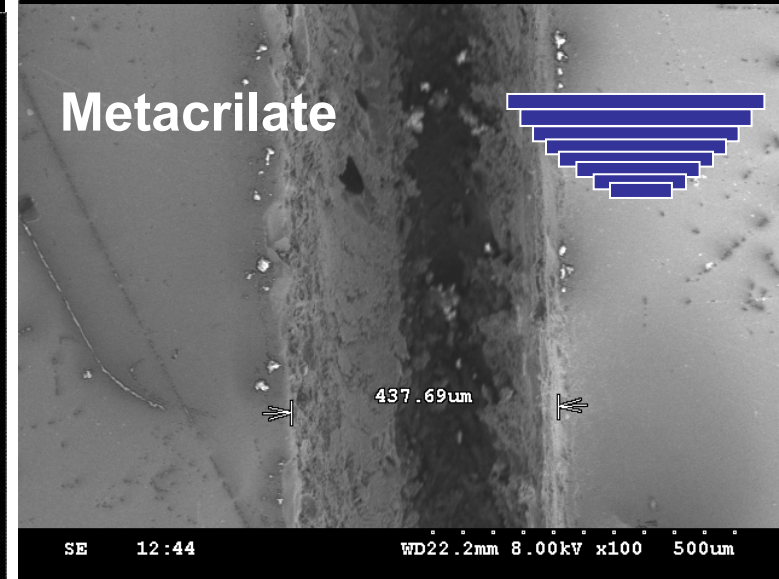
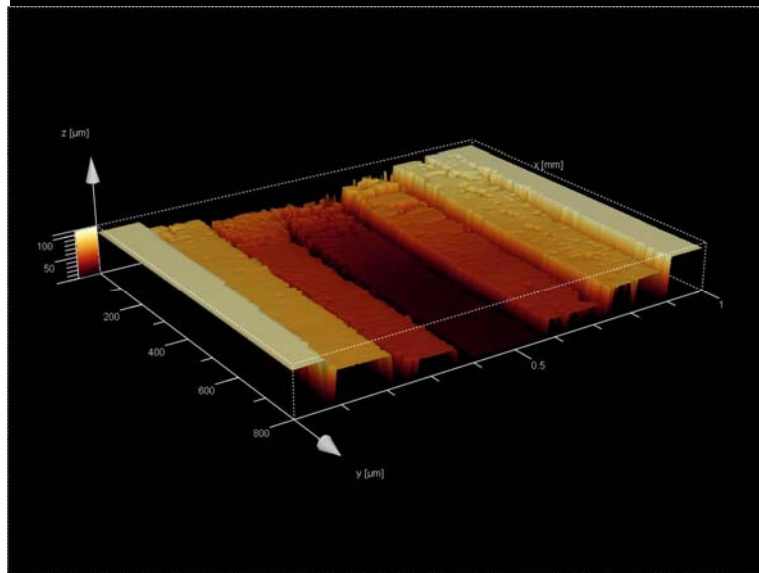
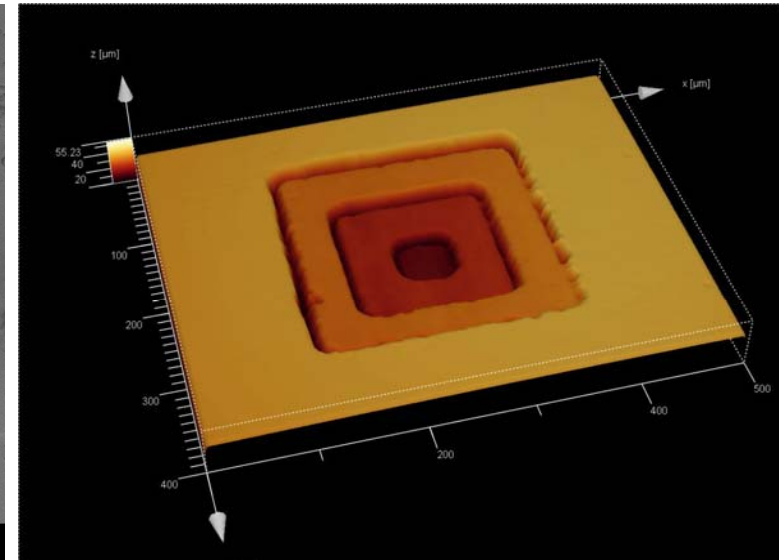
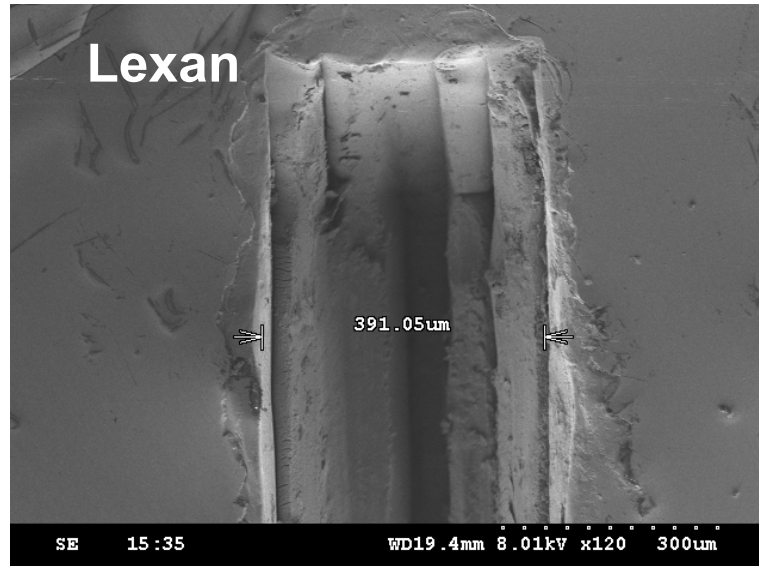
Mo
e=0.2 mm



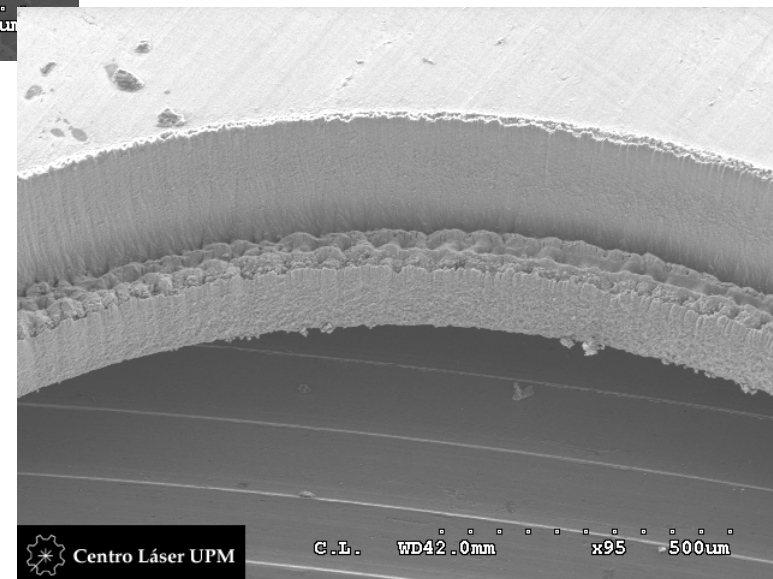
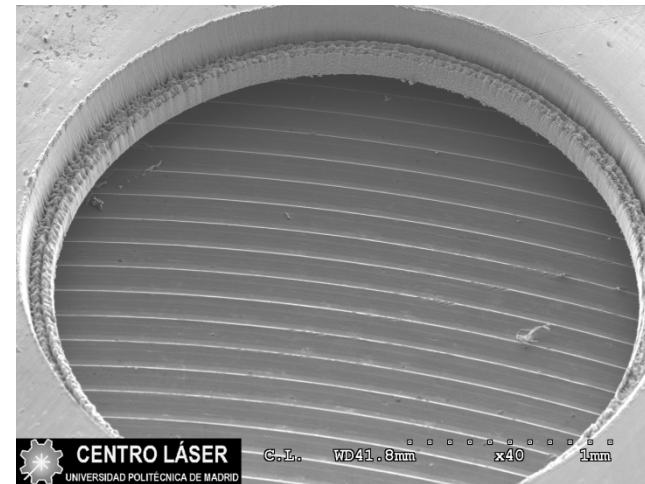
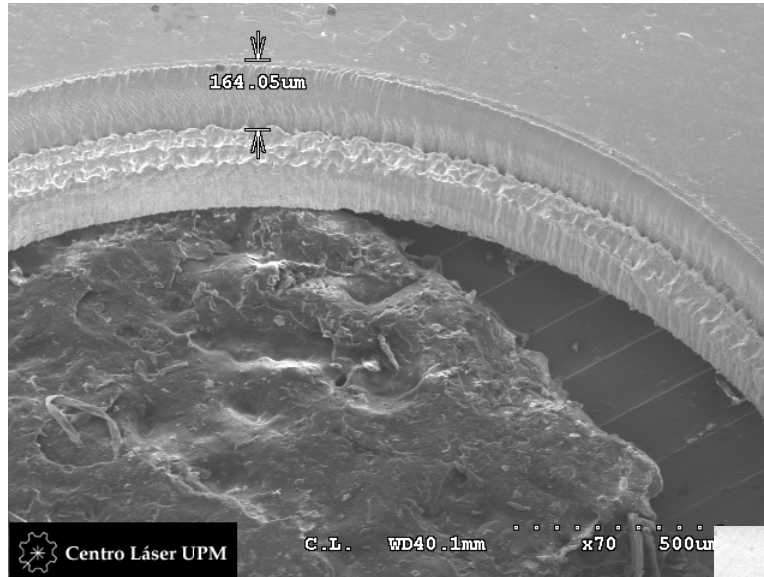
MICROGEARS CUTTING



MICROMILLING USING HYBRID TECHNIQUES



MICROMILLING: STEP GENERATION FOR ASSEMBLING

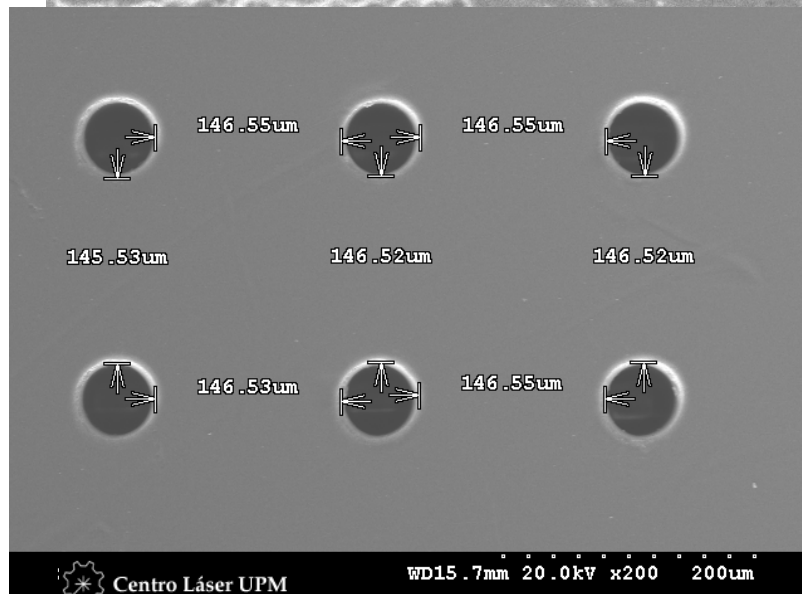
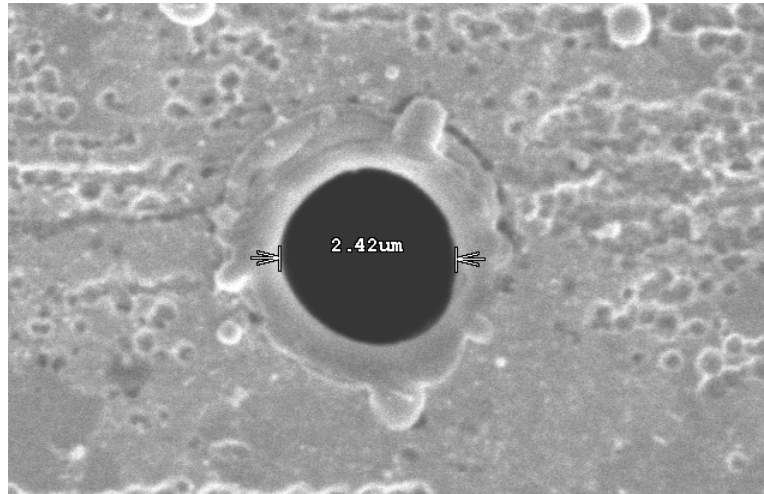


Material: Ta
e= 0.3 mm

Step Dimensions:
H:0.1 mm - W:0.05 mm

2D HOLE DRILLING

Planar

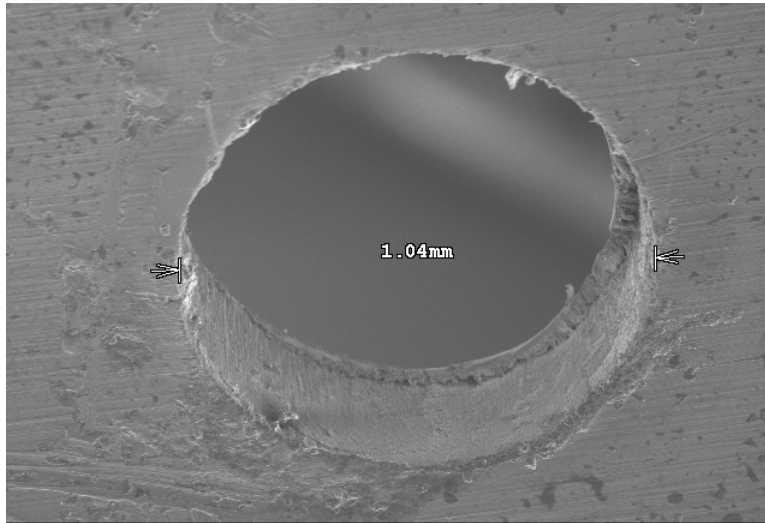


Fused Silica

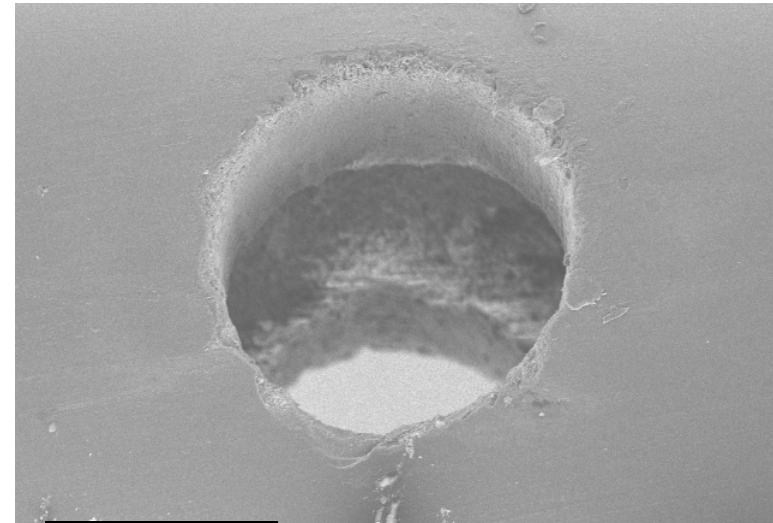


Cylindrical

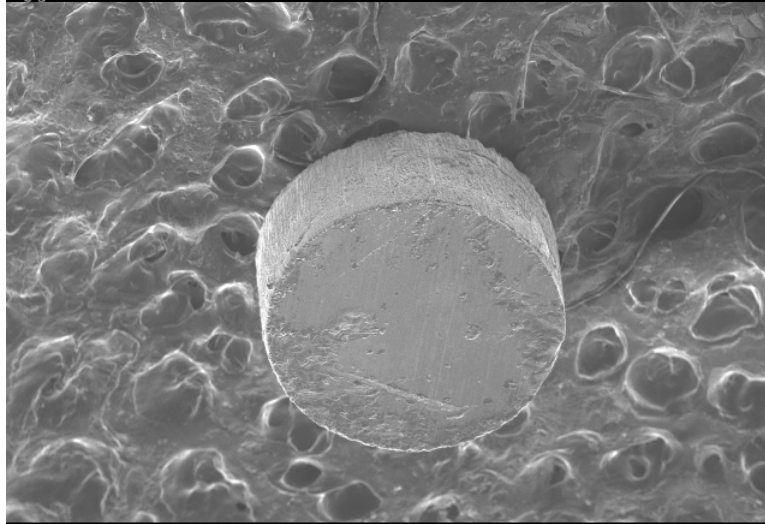
2D TREPPANNING



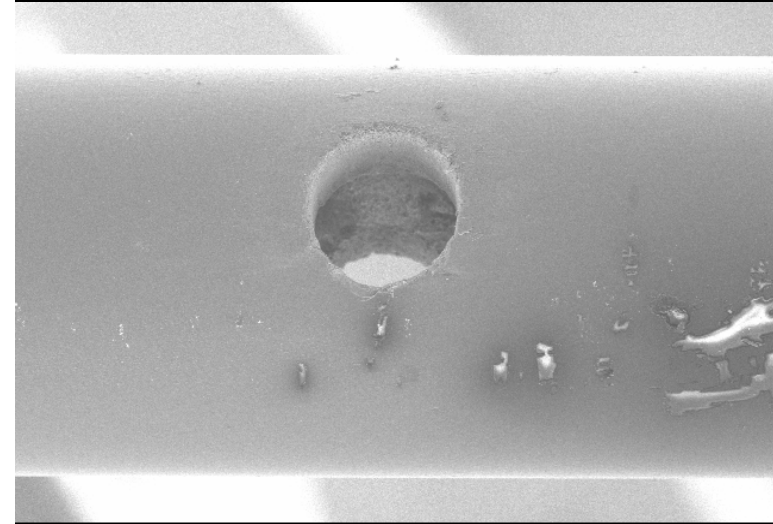
Centro Láser UPM WD22.6mm 8.03kV x75 500um



Centro Láser UPM WD11.8mm 10.0kV x200 200um

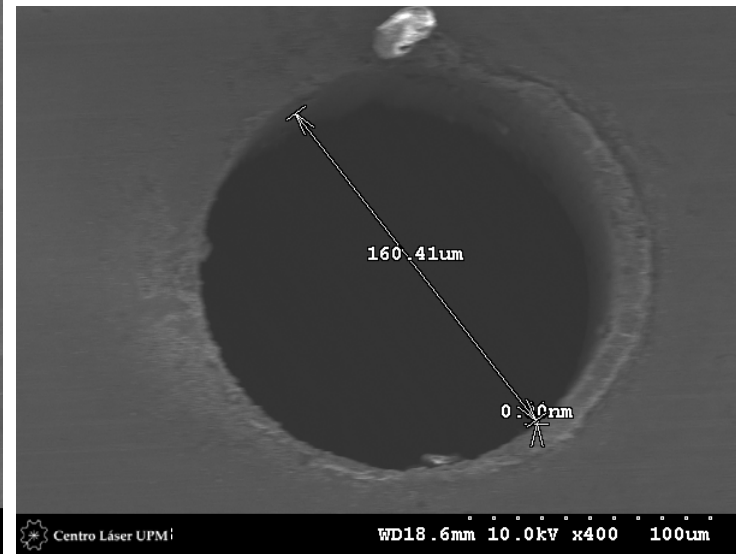
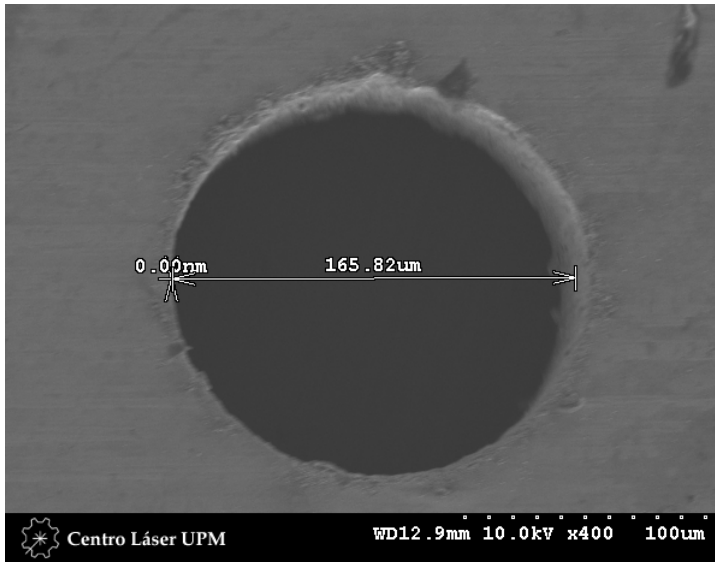


Centro Láser UPM WD23.4mm 8.03kV x50 1mm



Centro Láser UPM WD11.8mm 10.0kV x85 500um

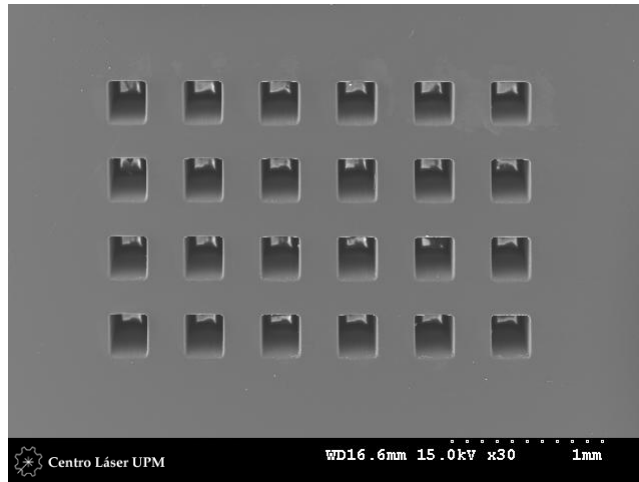
2D TREPPANNING



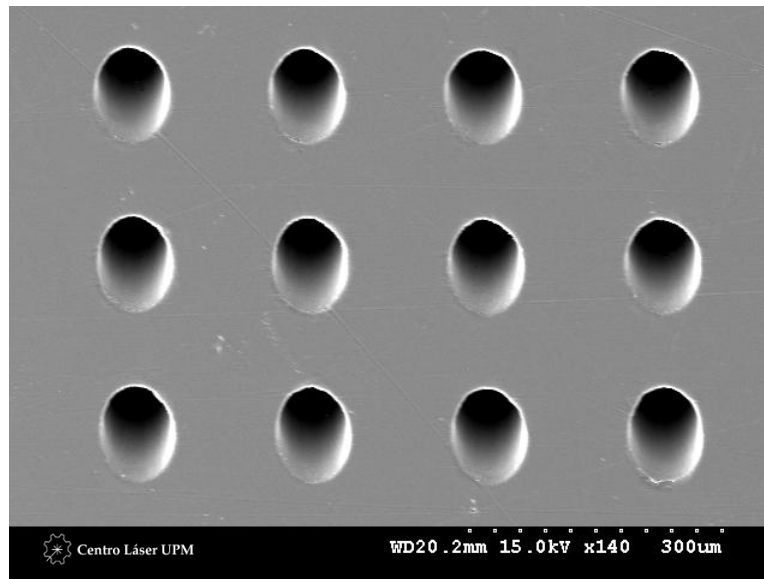
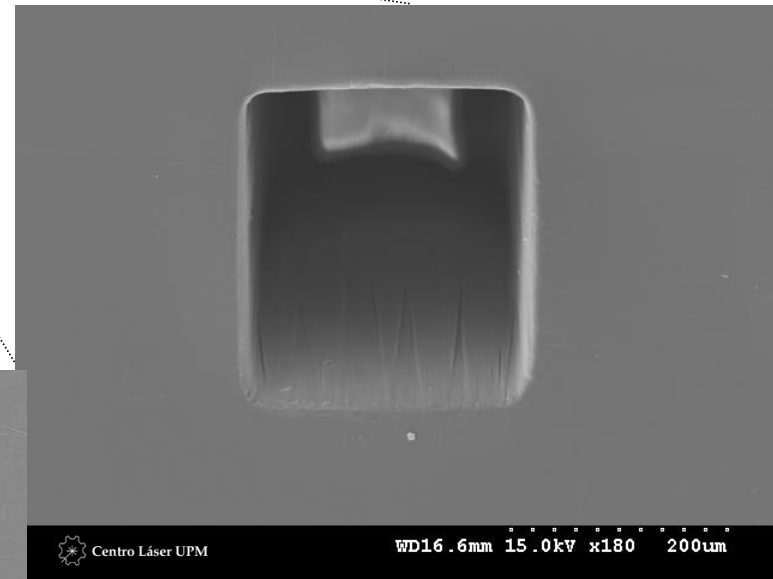
Steel: 1mm



CHANNELS FABRICATION WITH COLATITUDE CONTROL ($2 + \frac{1}{2} D$)



Polycarbonate



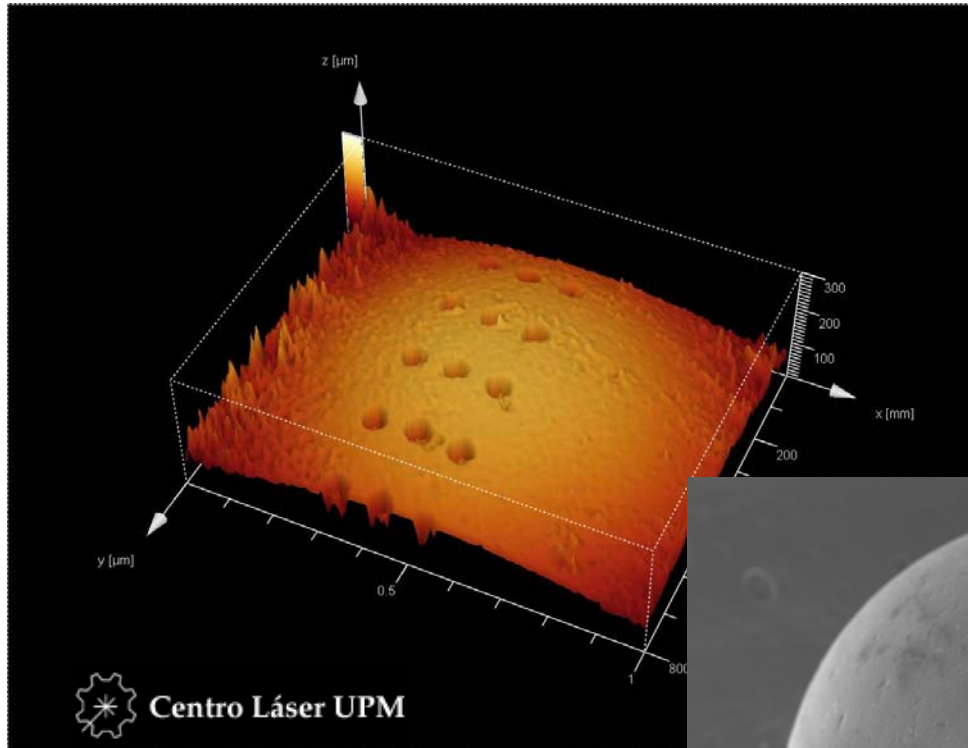
$e=1 \text{ mm}$

$L= 250 \mu\text{m}$

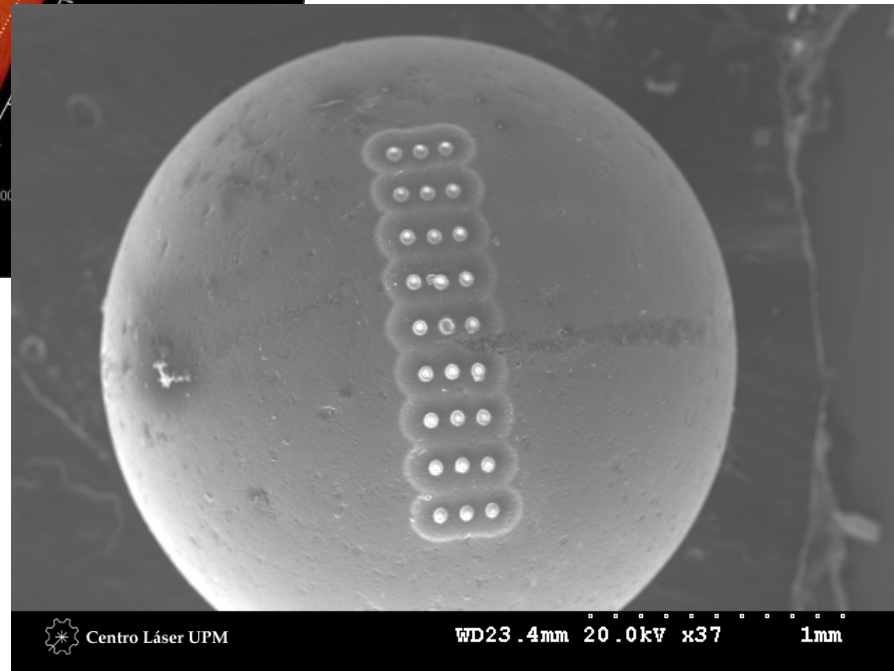
$\alpha= 30^\circ$

Circular section

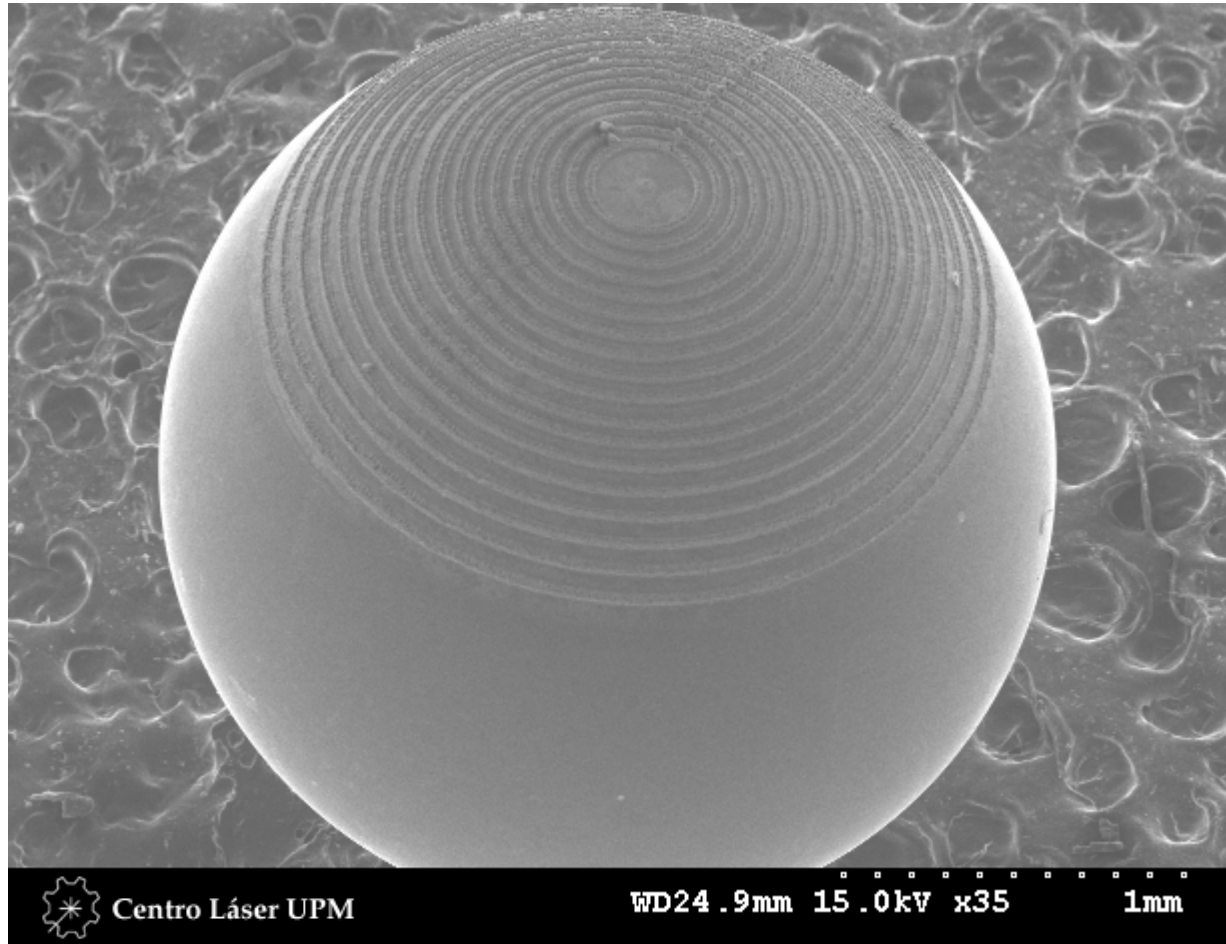
3D SURFACE TEXTURING



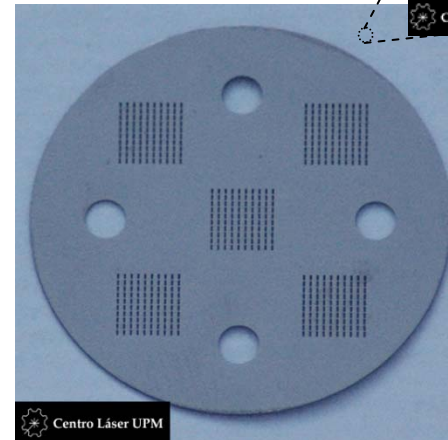
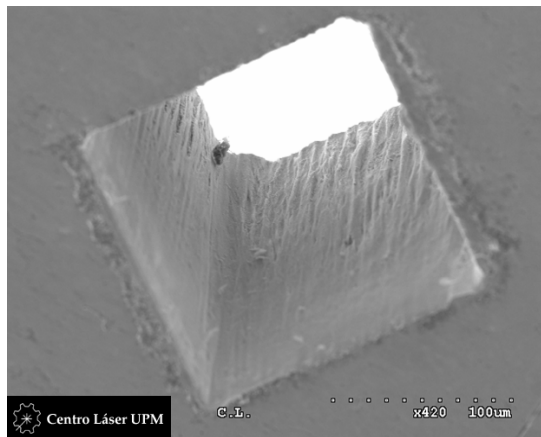
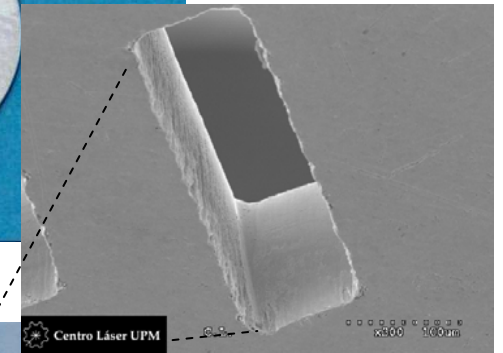
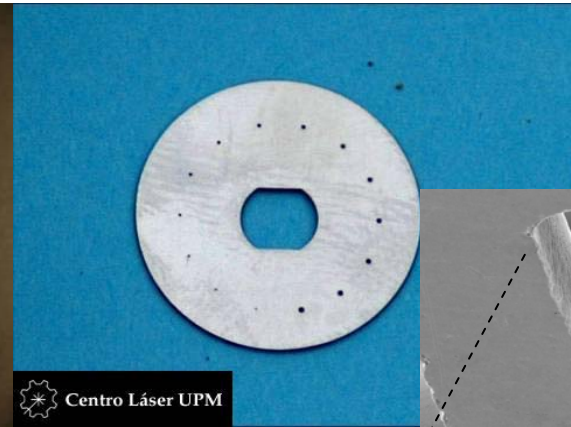
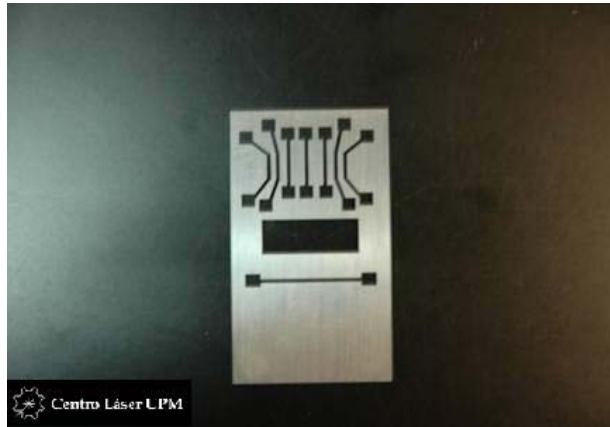
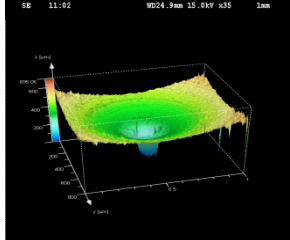
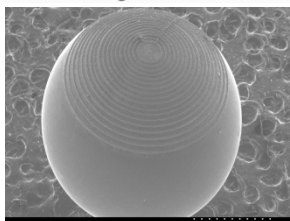
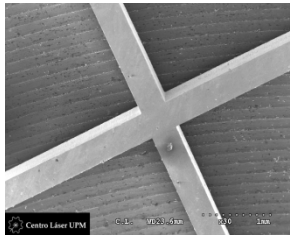
Sphere diameter = 2.5 mm
 $\Phi = 75 \mu\text{m}$



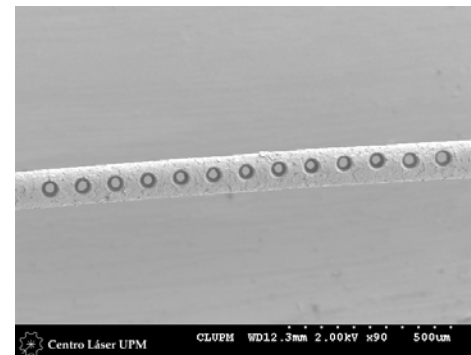
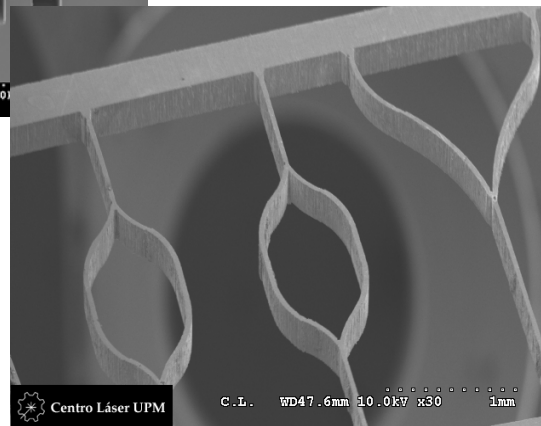
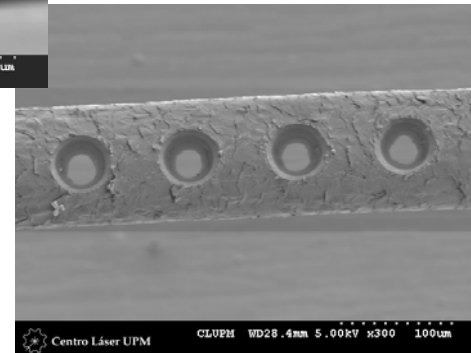
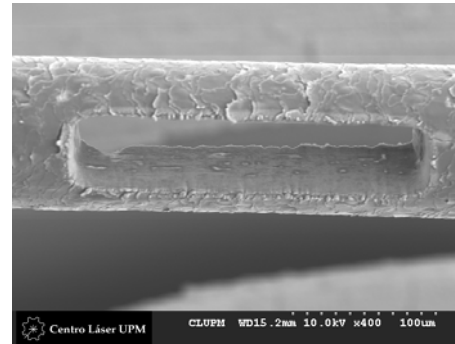
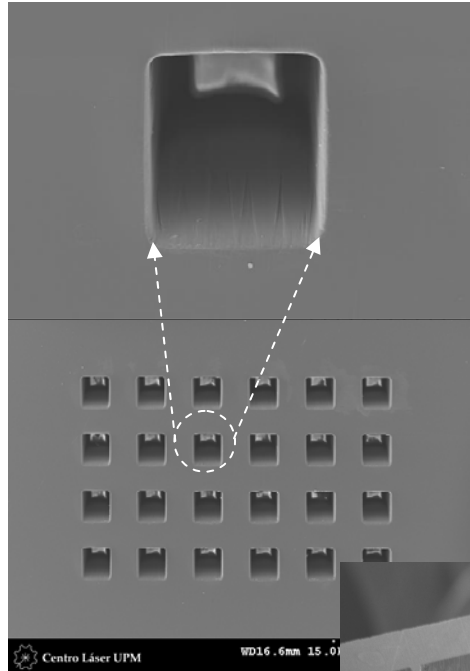
3D SURFACE TEXTURING



MICROMACHINING EXAMPLES



MICROMACHINING EXAMPLES



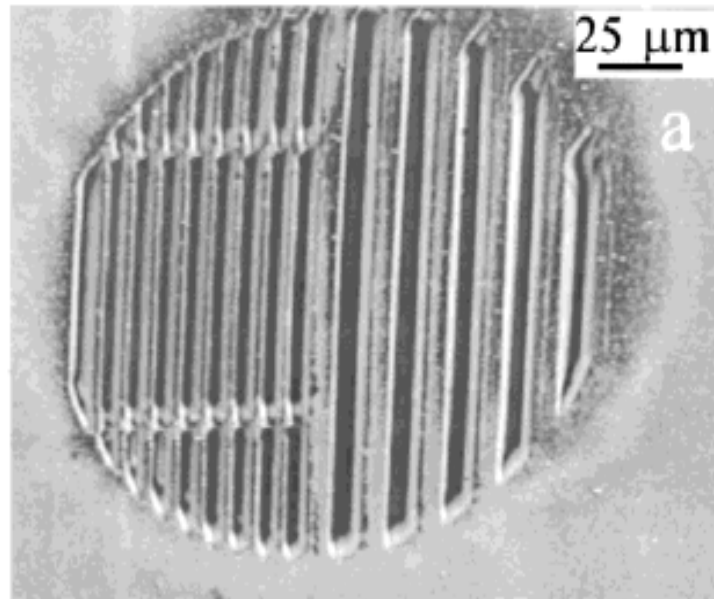
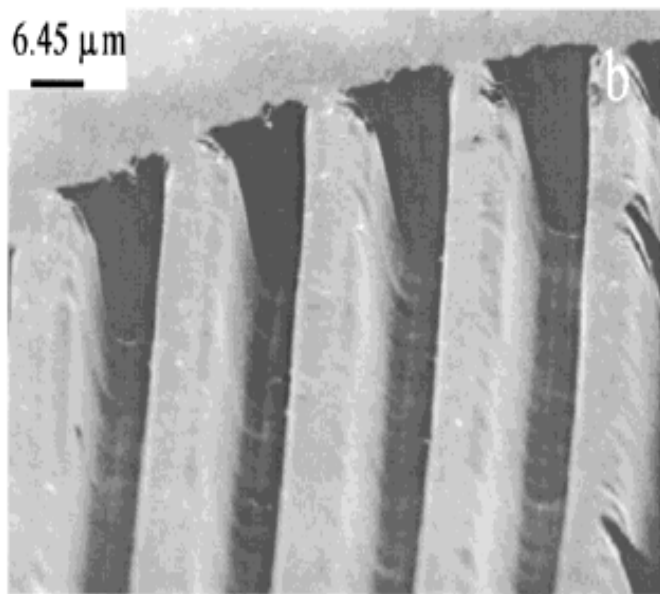
MICROPROCESSING: CML-100

CONCLUSIONS

- A prototype of a fully 3D flexible laser micromachining system has been designed and presently is completely operative
- Integration of excimer and DPSS UV laser in the same system has demonstrated to be an added value for this kind of equipment
- Complex geometries (concerning the workpiece and the pattern to be processed) have been obtained in different materials
- Nowadays there is an important demand for 2D and 2D + 1/2 applications and the appearance of fully 3D applications is expected for the next years

Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

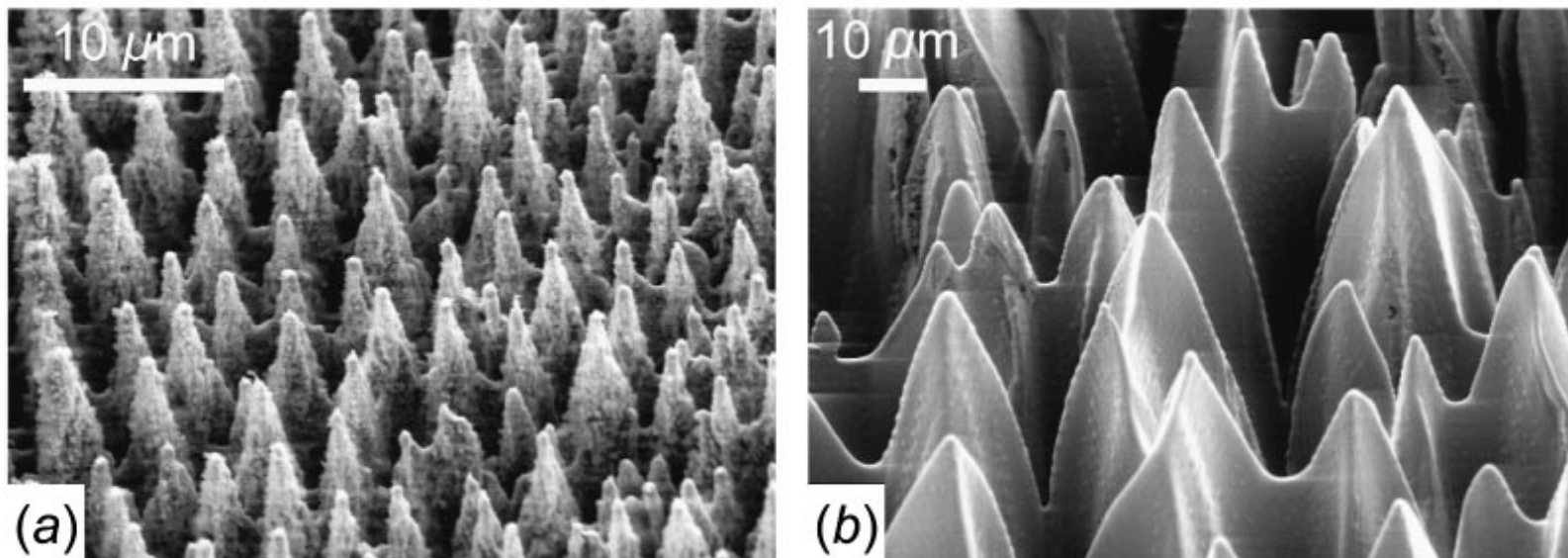
a. Laser surface microstructuring of polymeric surfaces



SEM micrographs of microstructures produced by a 20 ns pulse XeCl laser in different polymers : (a) structure in MP2C irradiated at 4.6 J cm^{-2} with 9 pulses; (b) structure in TM2C irradiated at 4.6 J cm^{-2} with 11 pulses.

Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

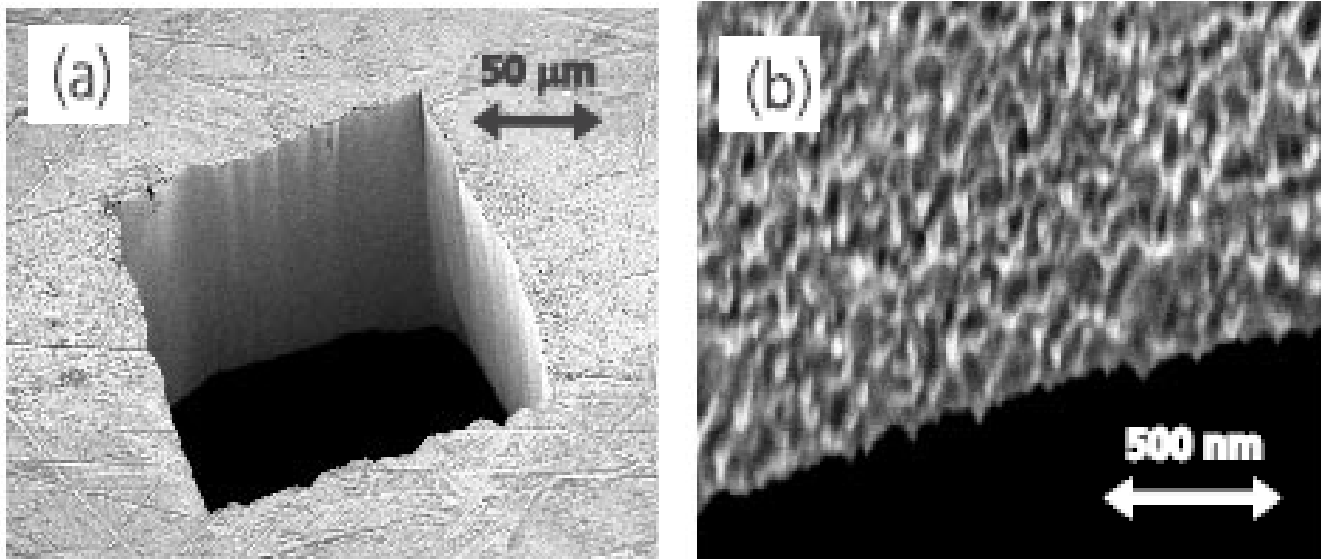
b) Laser surface microstructuring of semiconductors



Microstructures formed in crystalline Si by laser pulses: a) Ti:Sapphire laser of 100 fs pulse length up to 10 kJ/m² fluence; b) KrF laser of 30 ns pulse length up to 30 kJ/m² fluence.

Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

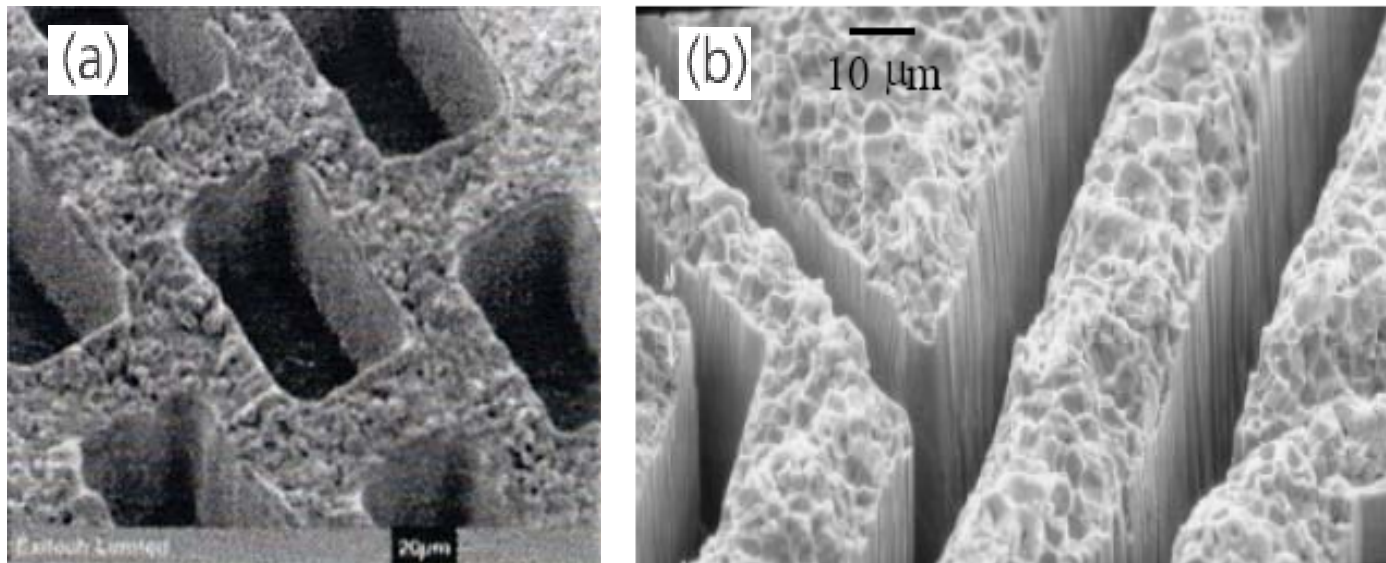
c) Laser surface microstructuring of metals and metallic alloys



Microstructure generated in a stainless steel sheet with KrF laser radiation.
a) Rectangular hole machined with 120-fs pulses at 1013 W/cm².; b) Magnified view of the microstructure of the exit edge of the exit edge of the same.

Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

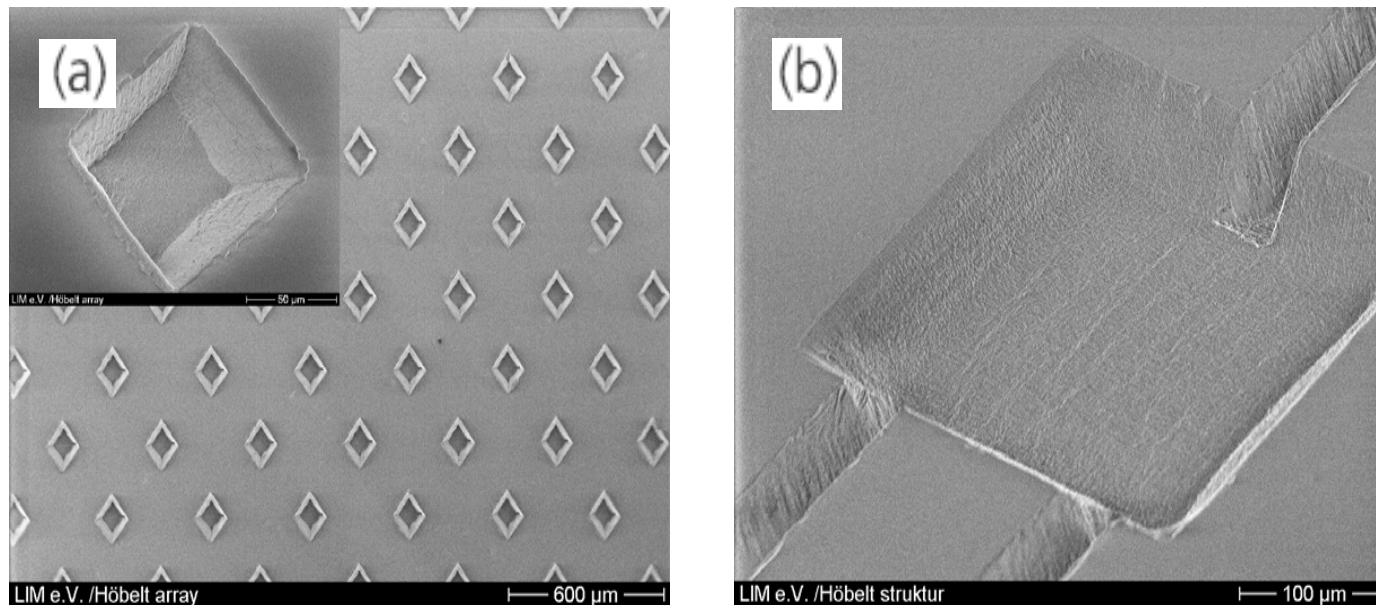
d) Laser surface microstructuring of glass and ceramics (1/2)



Samples of laser microstructuring of ceramic materials with high aspect ratio using a mask projection technique with UV lasers: a) alumina b) PZT

Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

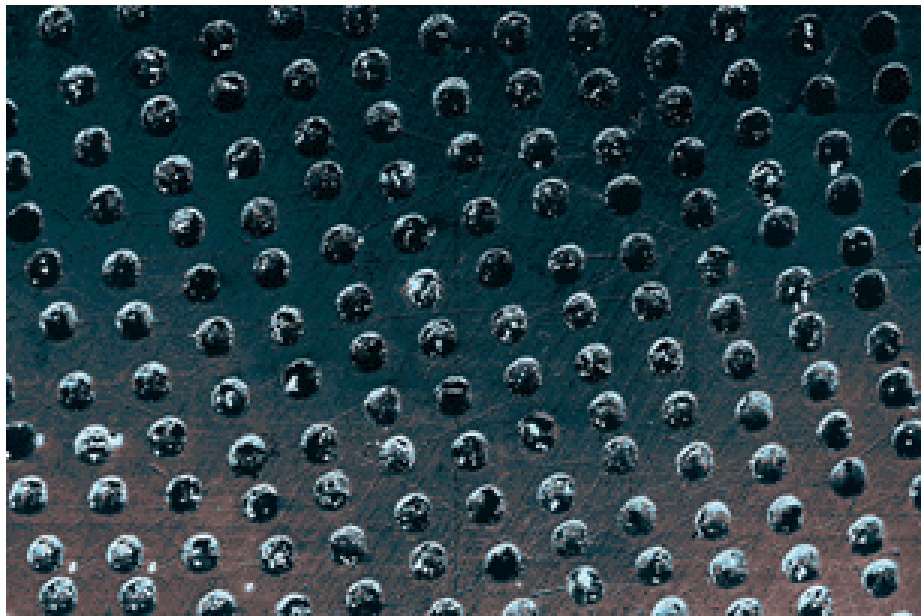
d) Laser surface microstructuring of glass and ceramics (2/2)



Laser generated structures in Pyrex® glass: a) Array of micro wells with 50 µm edge length and depth; b) cavity 350 x 350 x 55 µm³ with channels: 50 µm width, 55 µm depth.

Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

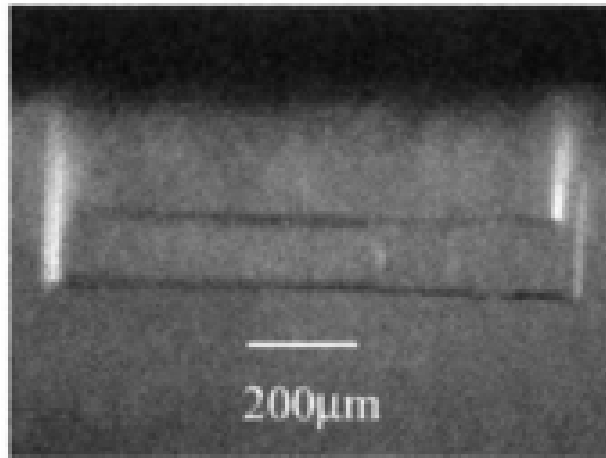
e) Laser Surface Texturing



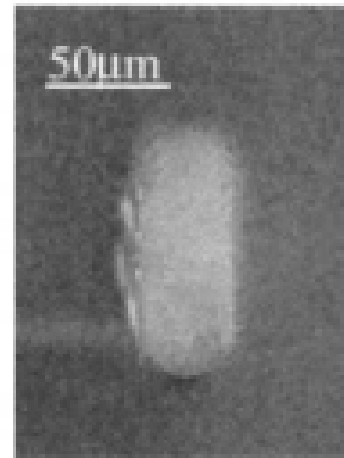
Regular micro-surface in the form of micro-dimples structured by ns laser.

Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

f) 3D Laser glass microstructuring



(a)



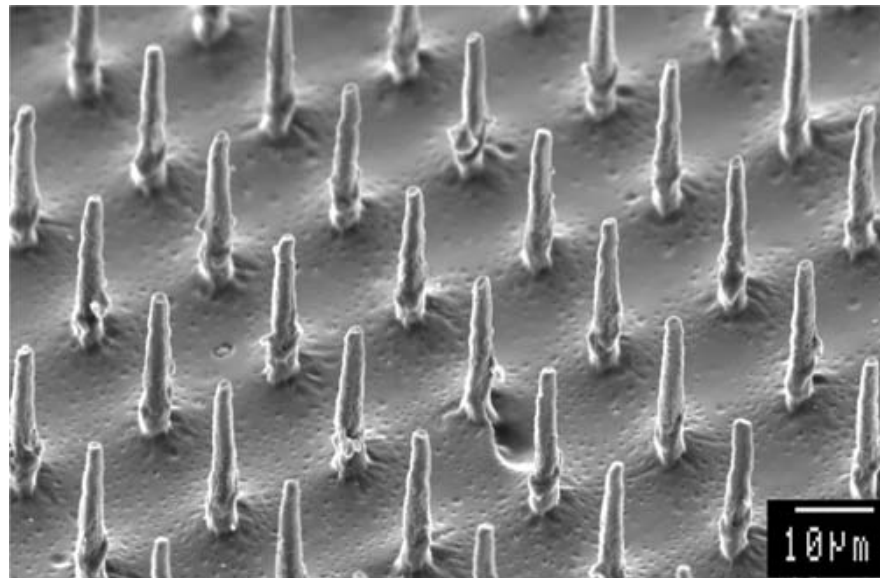
(b)

3D Bridge-like microstructure generated by a 140 fs, 775 nm laser in Foturan®.



Morphological Surface Microstructuring by High Intensity Short Pulse Laser Interaction

g) Microstructuring by laser sintering and other techniques



Scanning electron micrograph showing a microscopic pillar array fabricated by casting a heat shrunk polymer template. (Courtesy of A.J. Lee et al.: Appl. Phys. A 80, 1447–1449, 2005)



MICRO-FORMING

LSPSIM PARAMETERS

Nd:YAG Laser [nm]	1064
Energy per pulse [mJ]	33 - 150
Pulse length [ns]	9.4
Spot Radius [μm]	175
Target	SS304
Confining medium	Air
Interaction parameter α	0.2

ABAQUS PARAMETERS

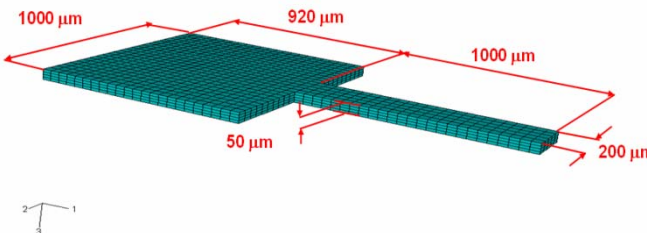
Pressure Pulse Temporal Evolution	LSPSIM
Pressure Pulse Spatial Distribution	Top Hat
Spot Center Position	variable

MATERIAL PROPERTIES (SS304)

Young's Modulus: E [GPa]	193
Poisson's Coefficient: ν	0.25
Density: ρ [kg/m^3]	7896
Melting Temperature: T_m [K]	1811
Test Temperature: T_0 [K]	300
Inelastic Heat Fraction: X	0.9
Johnson-Cook	
A [MPa]	350
B [MPa]	275
C	0.022
n	0.36
m	1
T_r [K]	300
$\dot{\epsilon}_0$ [s^{-1}]	1

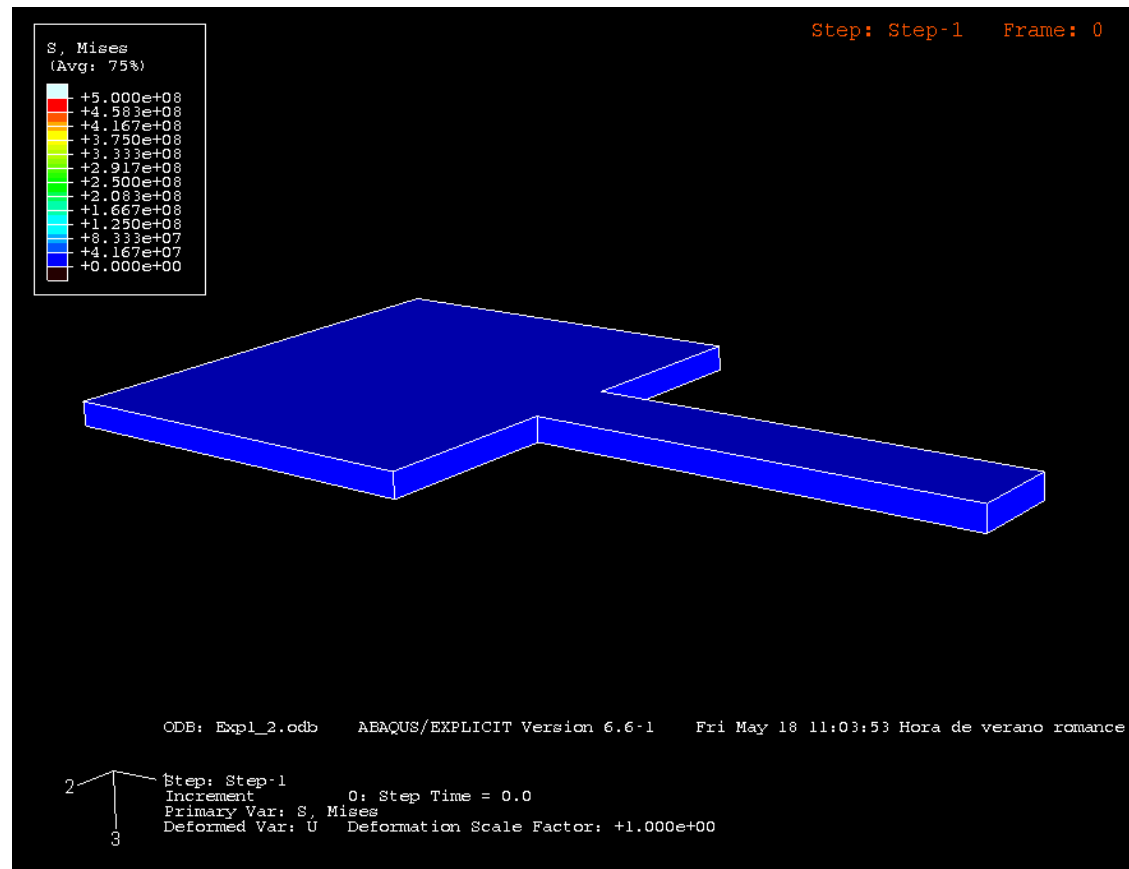
GEOMETRY AND DIMENSIONS

- **Boundary Conditions :**
pinned end.
- **Mechanical Simulation Elements:** C3D8R, 8-node brick reduced integration with hourglass control



MICRO-FORMING

ABAQUS EXPLICIT – VON MISES EVOLUTION

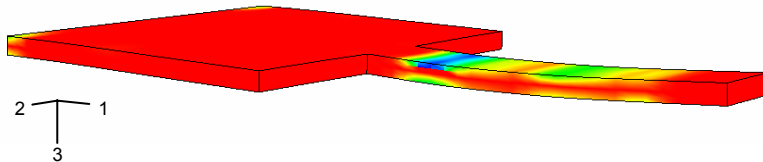
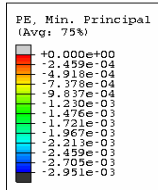


MICRO-FORMING

PLASTIC STRAIN

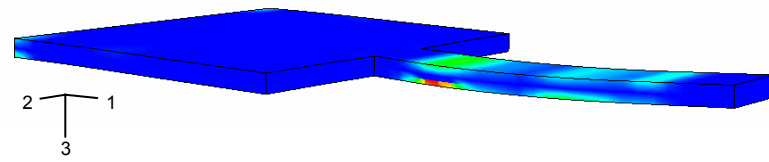
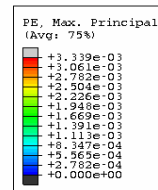
MIN. PRINCIPAL

Step: Step-1 Frame: 400



MAX. PRINCIPAL

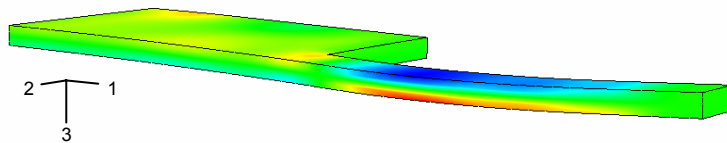
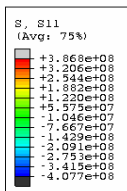
Step: Step-1 Frame: 400



STRESS DISTRIBUTION

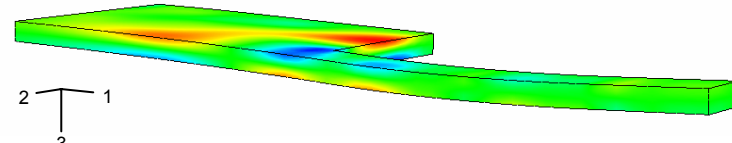
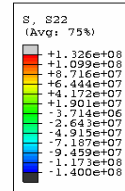
S11

Step: Step-1 Frame: 400



S22

Step: Step-1 Frame: 400

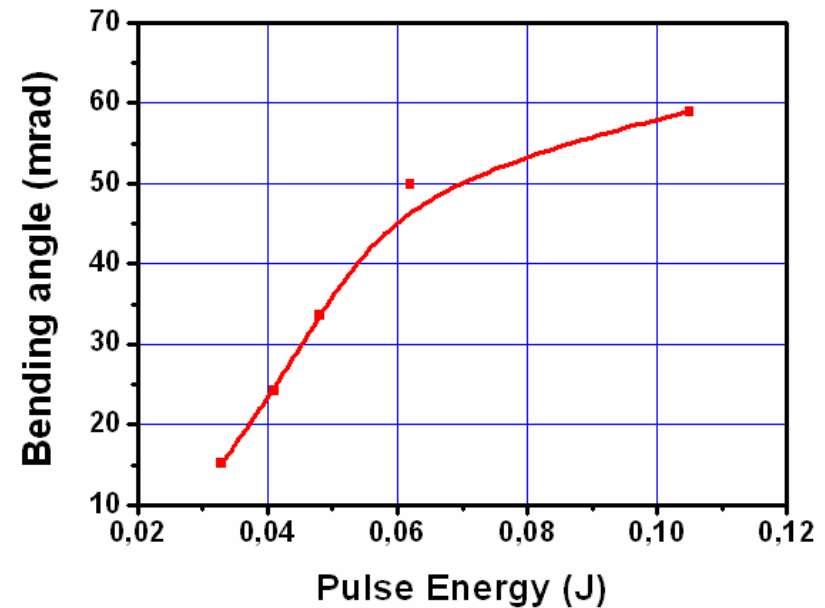
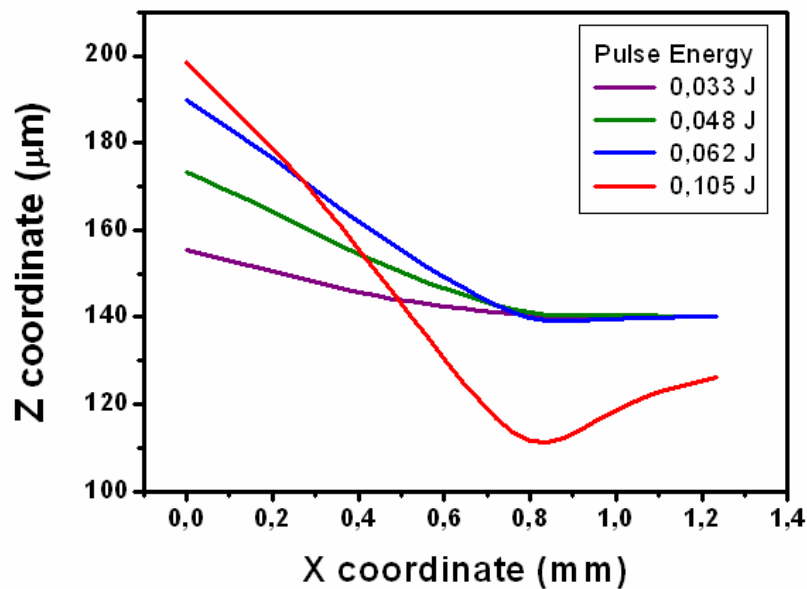


MICRO-FORMING

Pulse Energy Parametric Dependency

Nd:YAG Laser [nm]	1064
Energy per pulse [mJ]	variable
Pulse length [ns]	9.4
Spot Radius [μm]	175

Material Model	SS304 = JC
Confining medium	Air
Interaction parameter α	0.2
Spot center distance [μm]	150

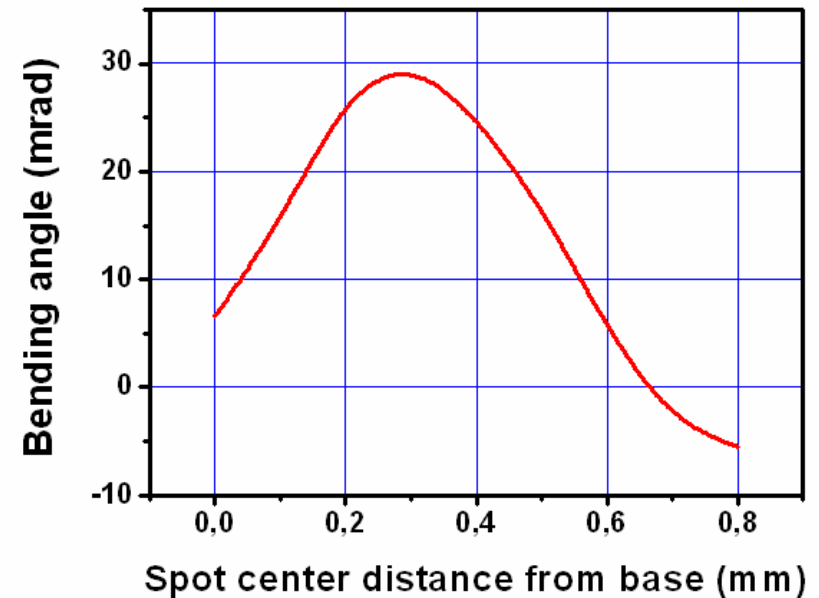
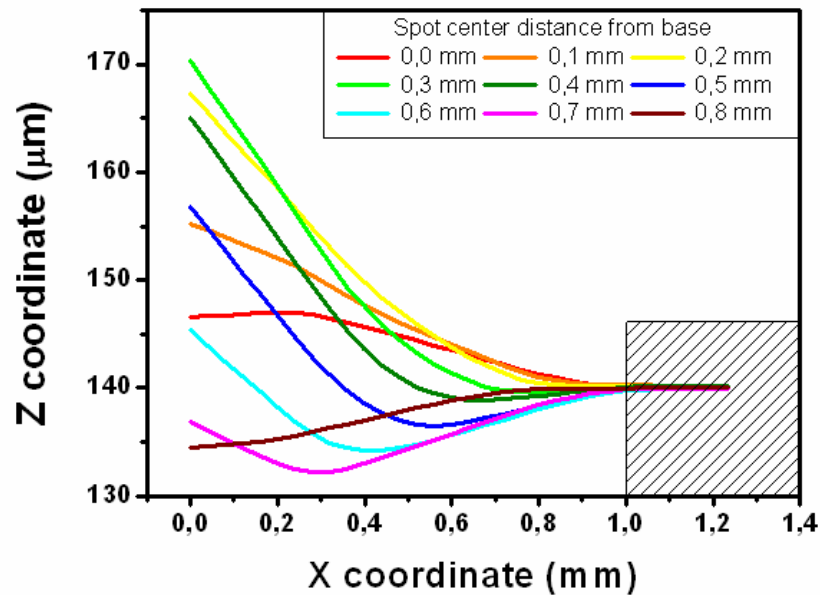


MICRO-FORMING

Spot Center Distance Parametric Dependency

Nd:YAG Laser [nm]	1064
Energy per pulse [mJ]	33
Pulse length [ns]	9.4
Spot Radius [μm]	175

Material Model	SS304 = JC
Confining medium	Air
Interaction parameter α	0.2
Spot center distance [μm]	variable

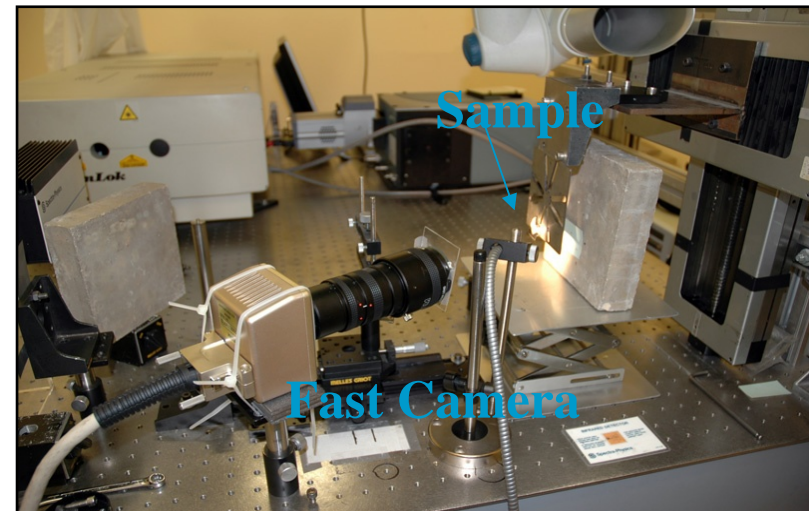


MICRO-FORMING

EXPERIMENTAL SETUP

MicroForming Parameters

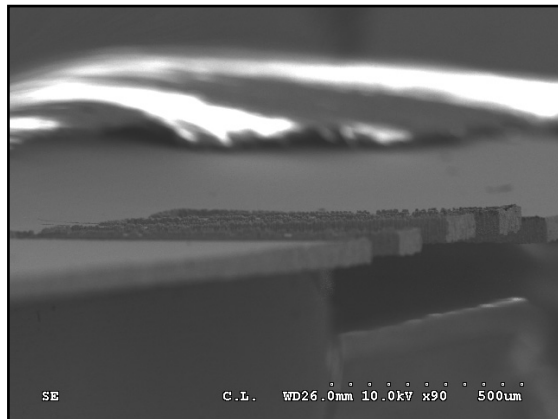
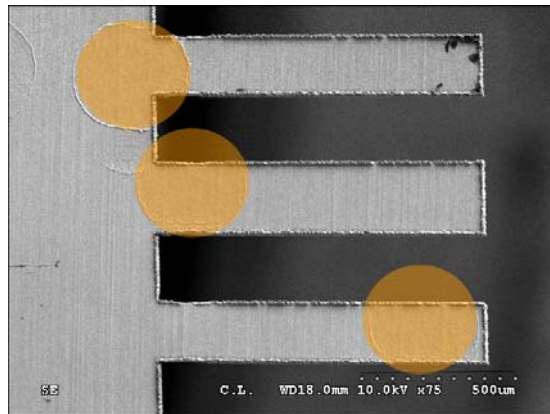
Nd:YAG Laser Wavelength [nm]	1064
Energy per pulse [J]	1.05
Pulse length FWHM [ns]	9.4
Beam radius (mm)	15
Mask radius [μm]	750
Energy per pulse (after mask) [J]	0.033
Spot radius [μm]	175
Confining layer	air



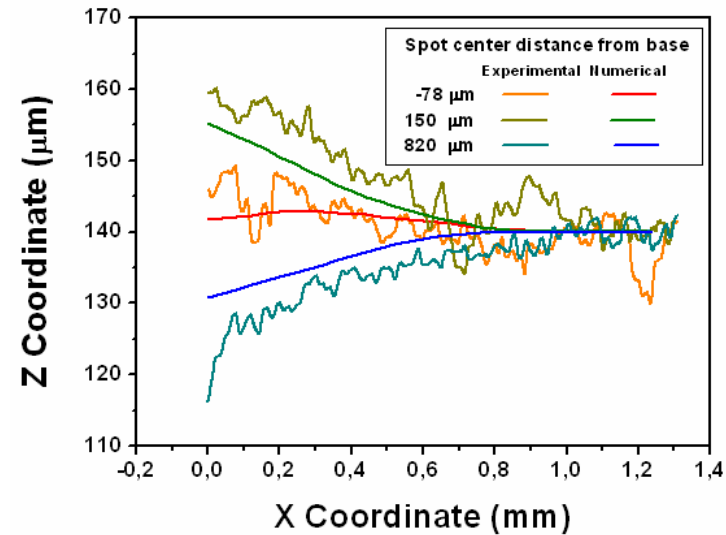
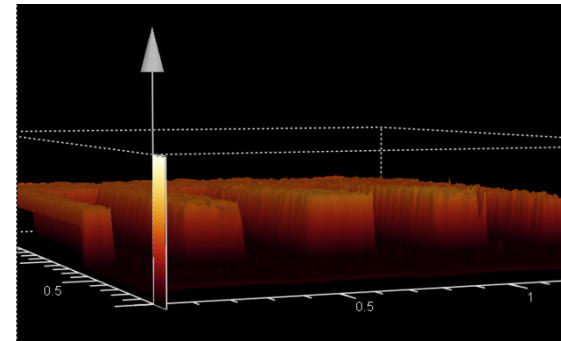
MICRO-FORMING

SPOT CENTER DISTANCE INFLUENCE

SEM IMAGES



CONFOCAL MICROSCOPY



MICRO-FORMING

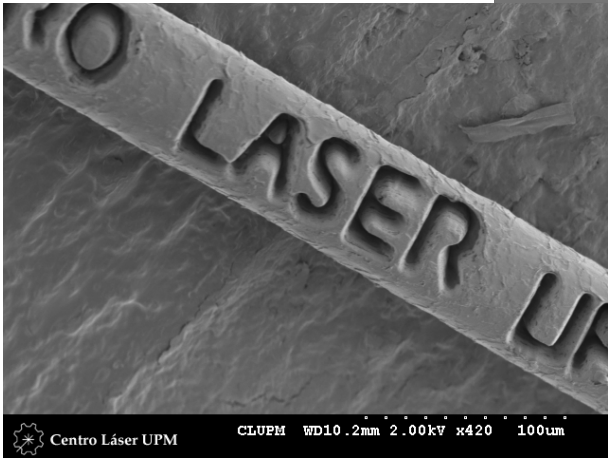
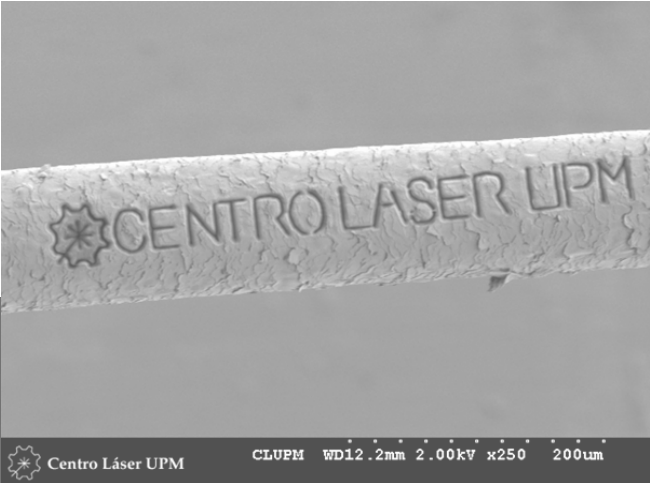
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ACKNOWLEDGEMENTS

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ABLATION



Inscription on human hair

Thank you !



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